

**ROCHESTER INSTITUTE OF TECHNOLOGY
MICROELECTRONIC ENGINEERING**

Optical Basics _MEMS

Dr. Lynn Fuller

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Microelectronic Engineering

Rochester Institute of Technology

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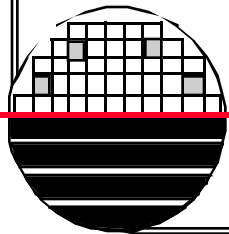
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Department Webpage: <http://www.microe.rit.edu>

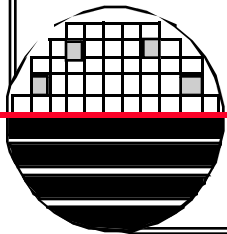


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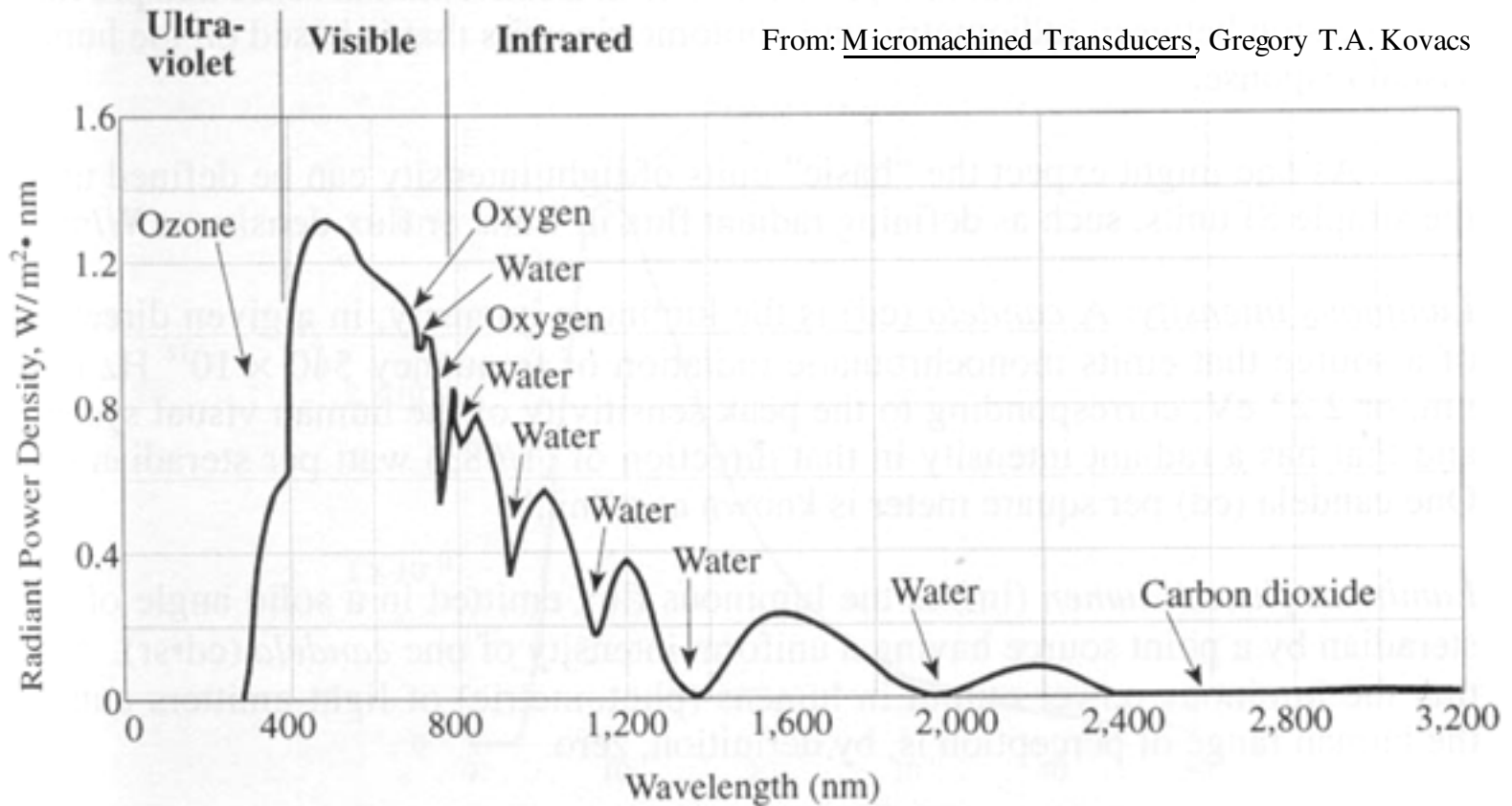
4-2-2013 Optical_Basics_MEMS.ppt

OUTLINE

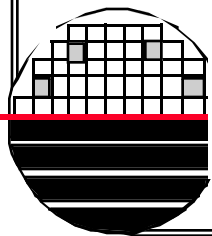
Light Sources
Light Detectors
Optic Components
Mirrors
Light Emissive Devices
Light Modulators
References
Homework



SPECTRICAL DISTRIBUTION OF SOLAR RADIANT POWER



From: Micromachined Transducers, Gregory T.A. Kovacs



Spectral distribution of solar radiant power density at sea level, showing the ozone, oxygen, water, and CO₂ absorption bands. After Benson (1992).

BLACK BODY, AM0 AND AM1.5

From: Solar Cells, Martin A. Green, Prentice Hall

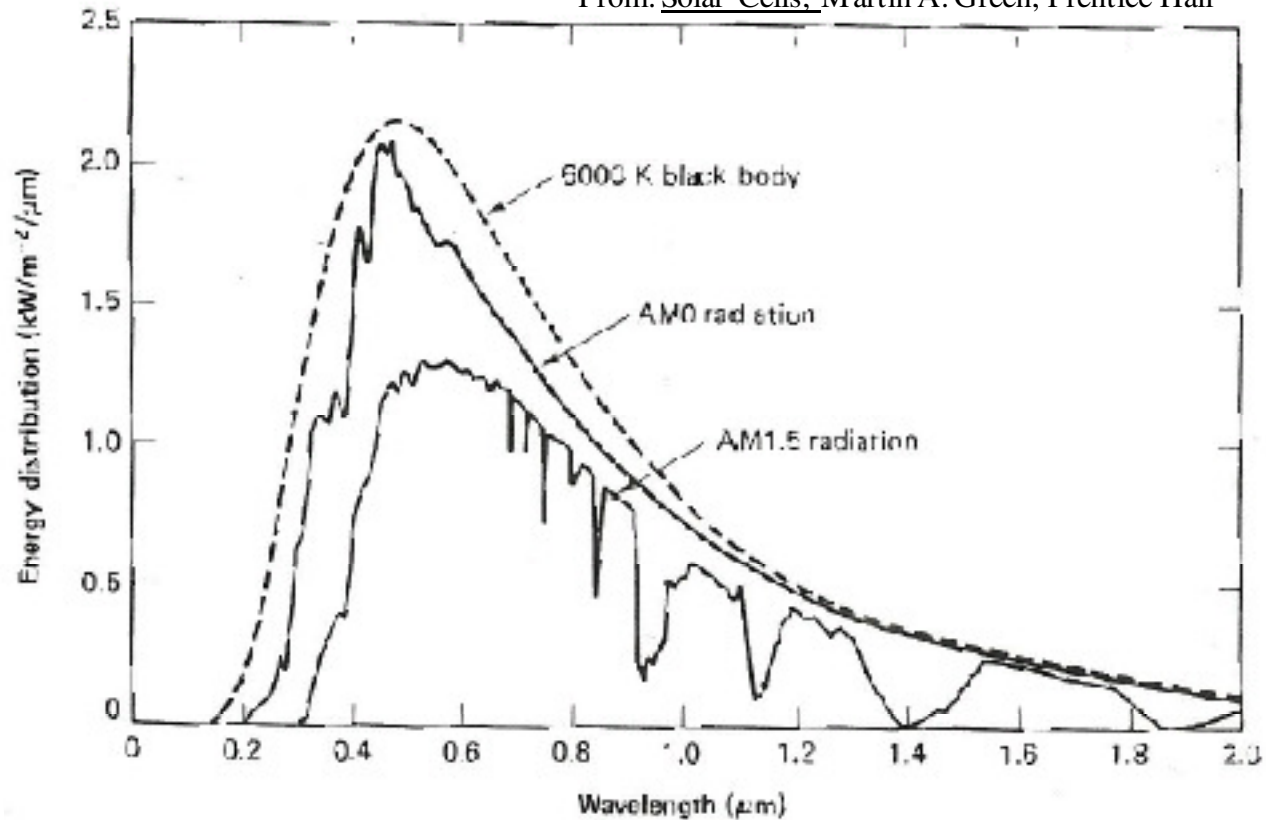
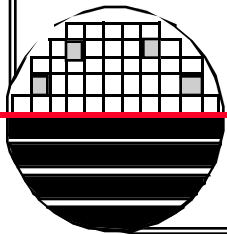
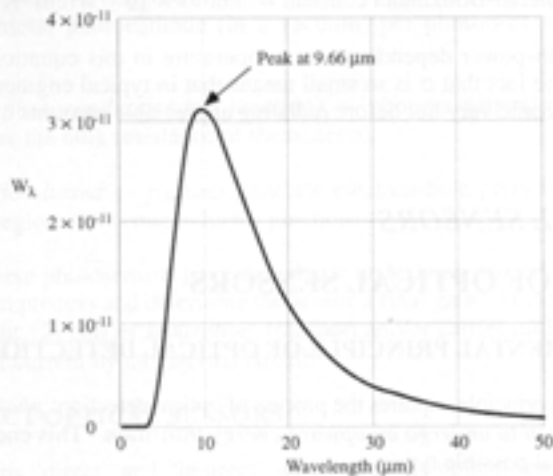


Figure 1.3. Spectral distribution of sunlight. Shown are the cases of AM0 and AM1.5 radiation together with the radiation distribution expected from the sun if it were a black body at 6000 K.



BLACK BODY RADIATION

From: Micromachined Transducers, Gregory T.A. Kovacs



Plot of W_λ versus λ (μm) for a 300 K (room temperature) object assuming $\epsilon = 1$ (human body temperature corresponds to a peak at $\approx 9.4 \mu\text{m}$).

$$W_\lambda = \frac{\epsilon(\lambda) 2\pi hc^2}{\lambda^5} \frac{1}{\left(e^{\frac{hc}{\lambda kT}} - 1 \right)} \text{ in W/m}^2$$

From: Solar Cells, Martin A. Green, Prentice Hall

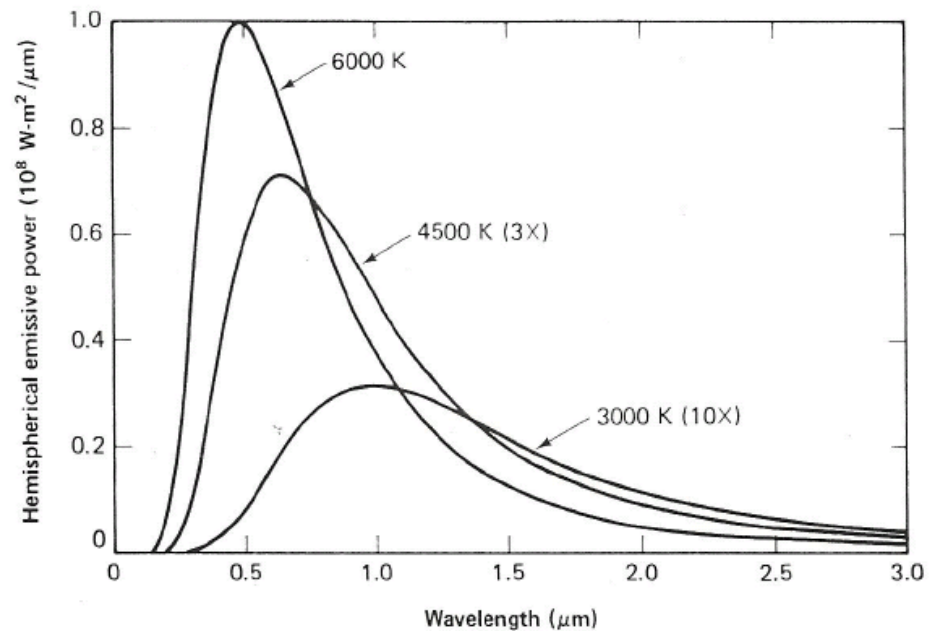
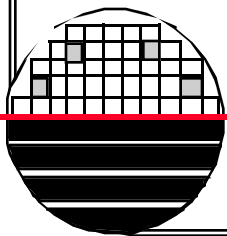


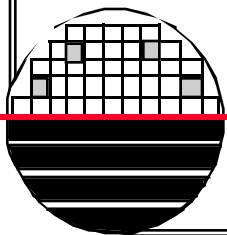
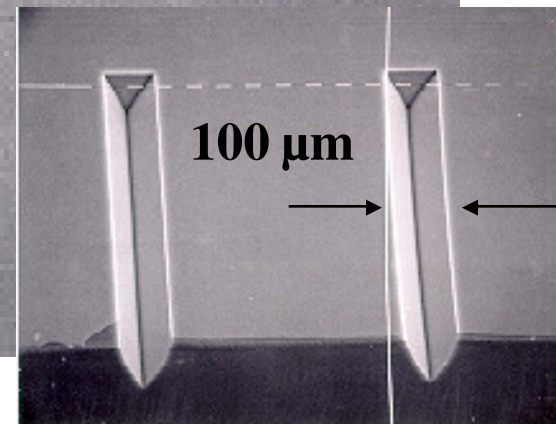
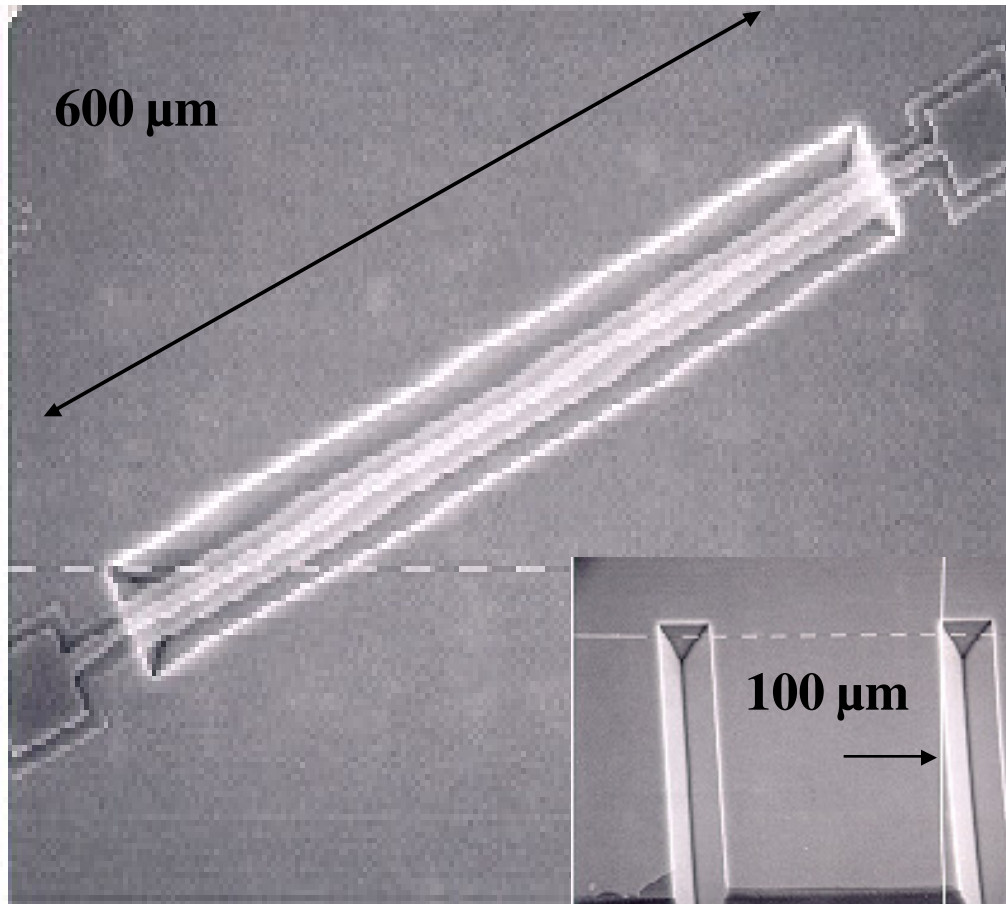
Figure 1.1. Planckian black-body radiation distributions for different black-body temperatures.



HOT FILIMENT "BLACK BODY" LIGHT SOURCES

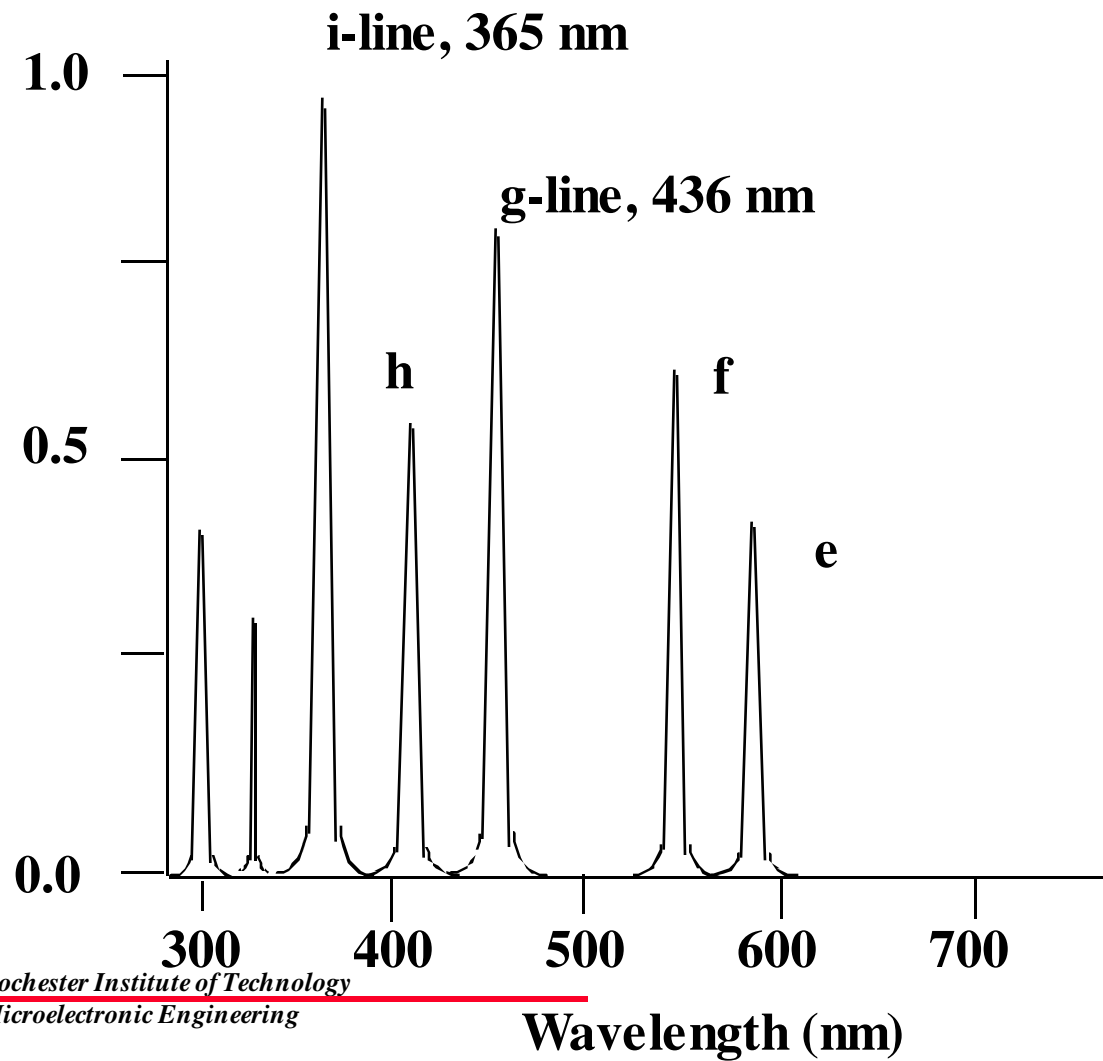
Dave Borkholder
Senior project 1993

MOVIE



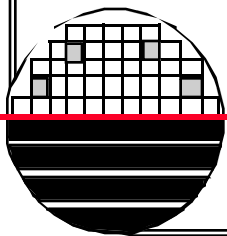
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EMISSION SPECTRA OF THE Hg VAPOR BULB



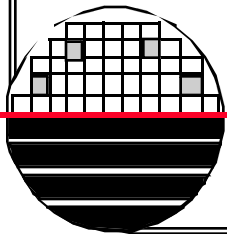
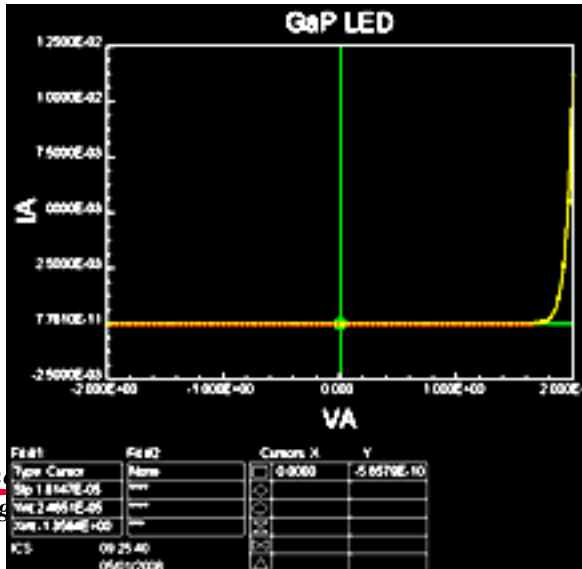
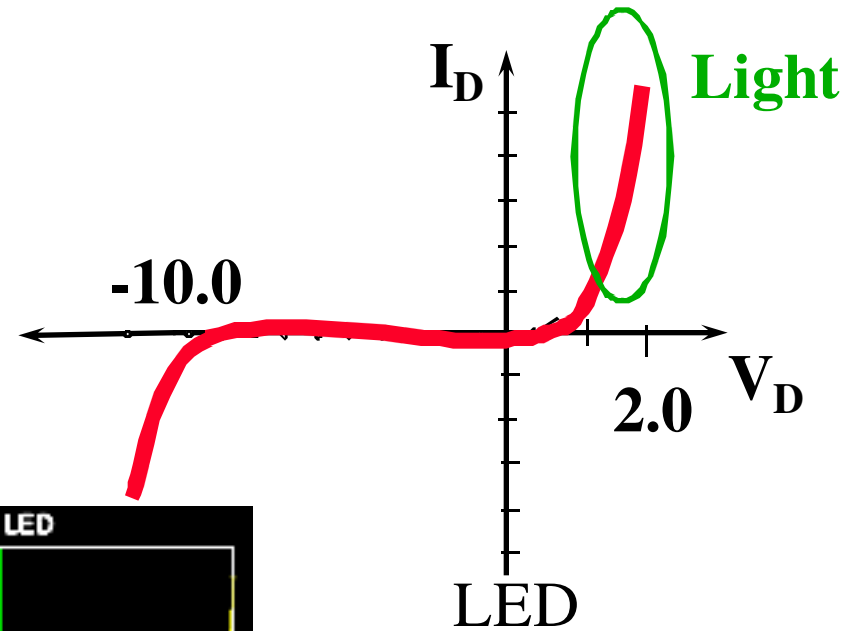
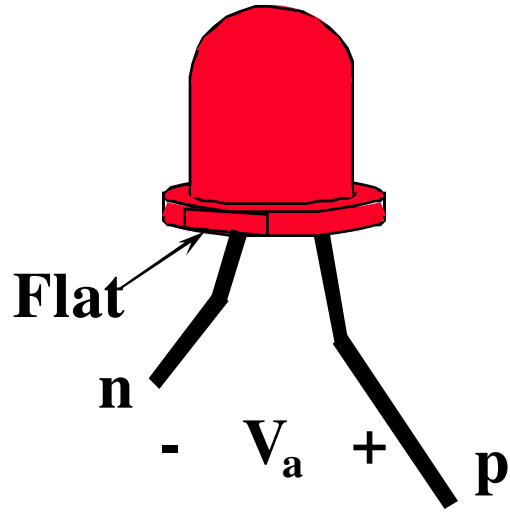
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Wavelength (nm)



LED IV CHARACTERISTICS

Light Emitting Diode -LED

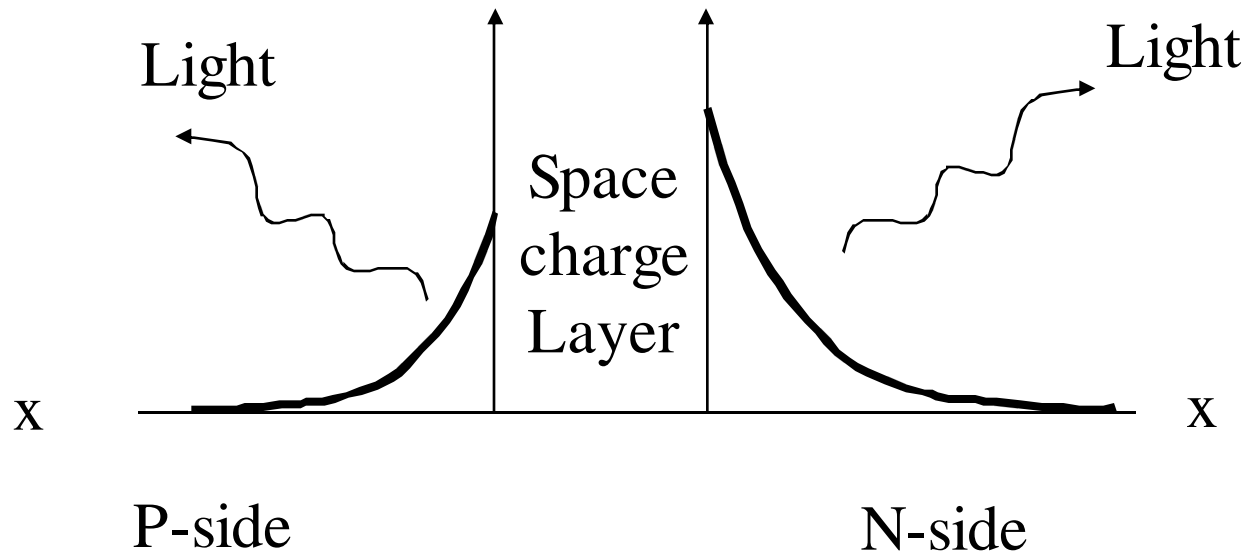


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LIGHT EMITTING DIODES (LEDs)

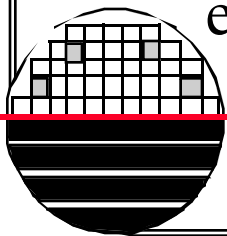
Electron concentration vs distance

Hole concentration vs distance

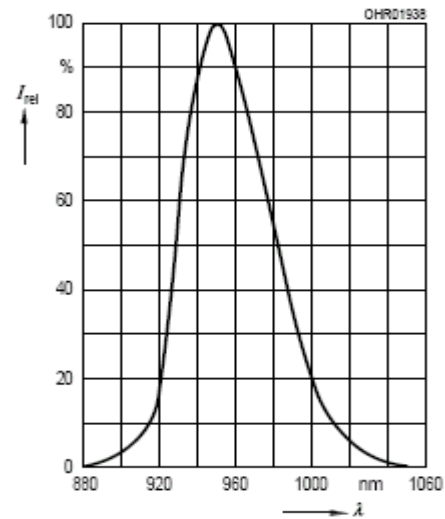
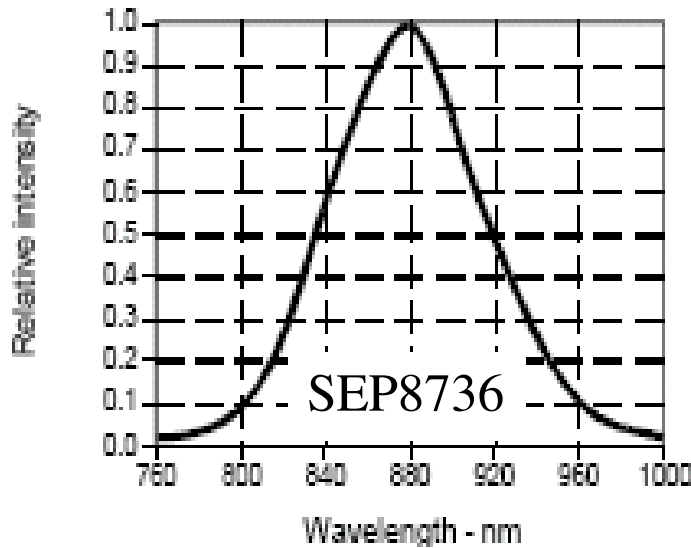


In the forward biased diode current flows and as holes recombine on the n-side or electrons recombine on the p-side, energy is given off as light, with wavelength appropriate for the energy gap for that material. $\lambda = h c / E$

h = Plank's constant
 c = speed of light



LEDs



SFH4110

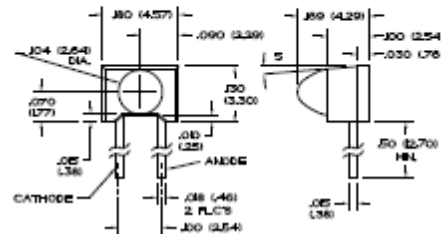


INFRA-8017

OUTLINE DIMENSIONS in inches (mm)

Tolerance 3 plc decimals $\pm 0.005(0.12)$

2 plc decimals $\pm 0.020(0.51)$



SEP8736

AlGaAs Infrared Emitting Diode

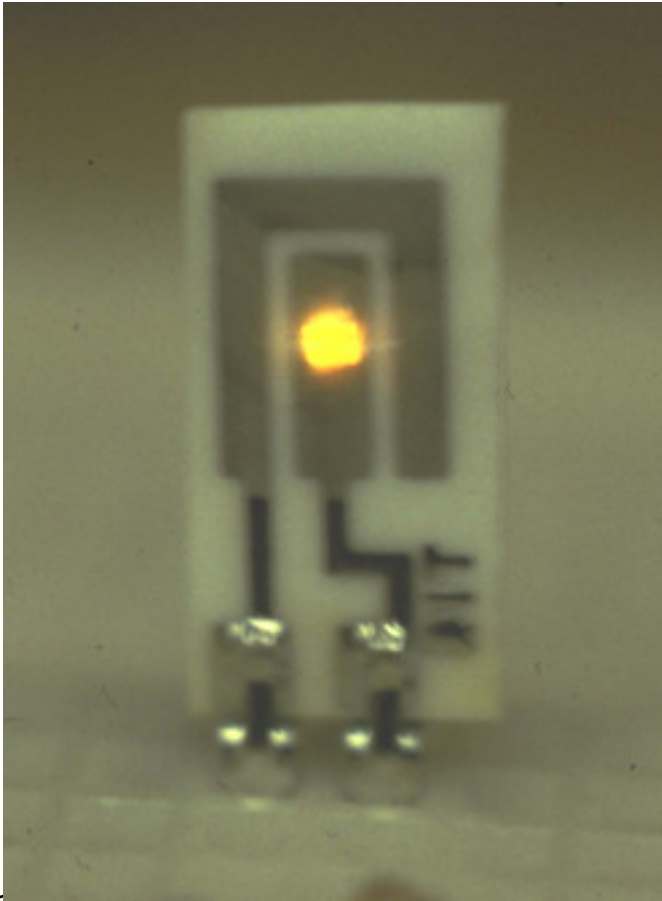
ELECTRICAL CHARACTERISTICS (25°C unless otherwise noted)

PARAMETER	SYMBOL	MIN	TYP	MAX	UNITS	TEST CONDITIONS
Irradiance ⁽¹⁾	H				mW/cm ²	$I_f=20$ mA
SEP8736-001		0.5				
SEP8736-002		1.2		3.0		
SEP8736-003		1.7				
Forward Voltage	V_F			1.7	V	$I_f=20$ mA
Reverse Breakdown Voltage	V_{BR}	3.0			V	$I_R=10$ μ A
Peak Output Wavelength	λ_p		880		nm	
Spectral Bandwidth	$\Delta\lambda$		80		nm	
Spectral Shift With Temperature	$\Delta\lambda_p/\Delta T$		0.2		nm/°C	
Beam Angle ⁽²⁾	θ		10		degr.	$I_f=Constant$
Radiation Rise And Fall Time	t_r, t_f		0.7		μ s	

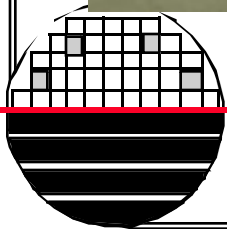
Notes

1. Measured in mW/cm² into a 0.104 (2.64) diameter aperture placed 0.500 (12.7) from the lens tip.
2. Beam angle is defined as the total included angle between the half intensity points.

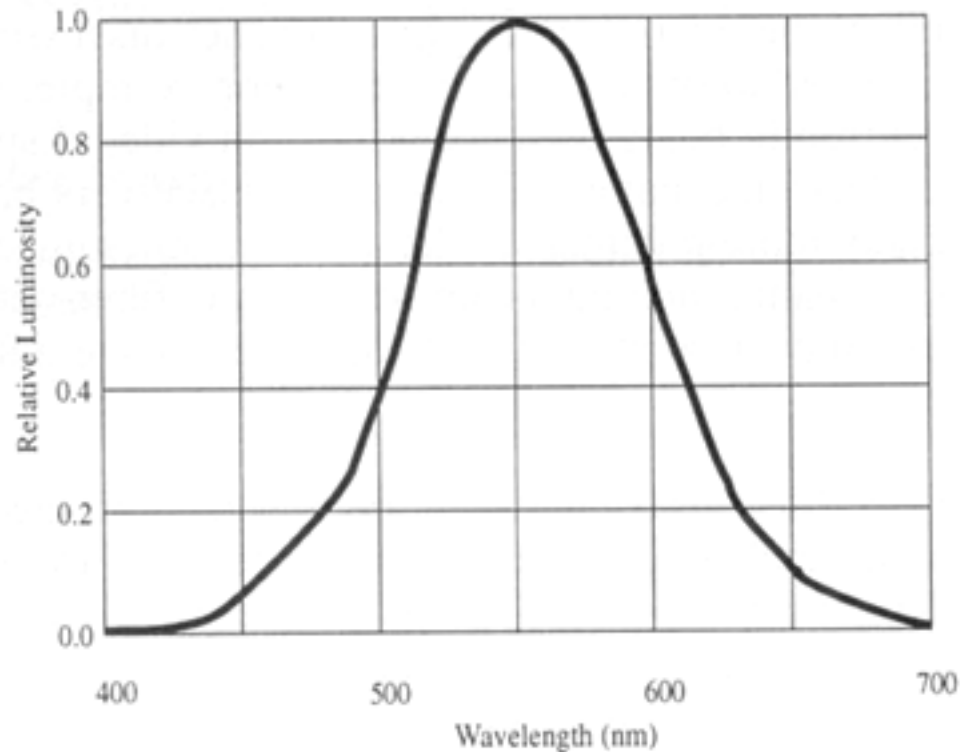
RIT'S FIRST LED



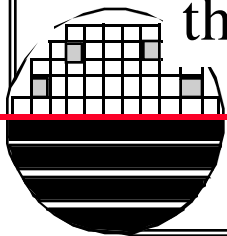
GaP wafers with n-type epilayer, add gold metal, dice and wire bond to RIT thick film ceramic package.



RELATIVE LUMINOSITY VS WAVELENGTH

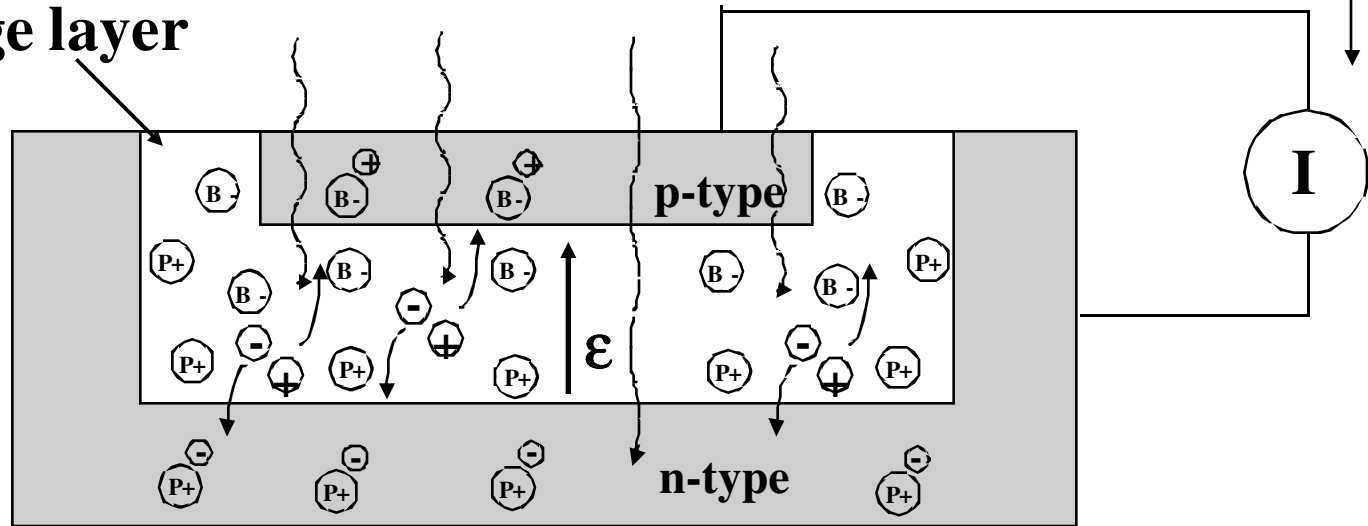


Human eye perceives 550nm (green-yellow) as the brightest, the relative luminosity of other colors is give above

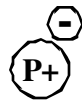


PHOTODIODE

space charge layer



electron
and hole
pair



Phosphorous donor atom and electron



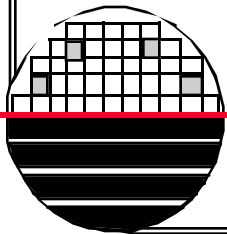
Ionized Immobile Phosphorous donor atom



Ionized Immobile Boron acceptor atom



Boron acceptor atom and hole



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WIDTH OF SPACE CHARGE LAYER

Width of space charge layer depends on the doping on both sides and the applied reverse bias voltage and temperature.

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PN.XLS
 4/13/2011

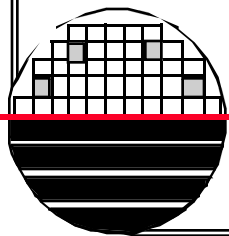
CALCULATIONS FOR PN JUNCTION (ELECTROSTATICS) DR. LYNN FULLER

To use this spreadsheet change the values in the white boxes. The rest of the sheet is protected and should not be changed unless you are sure of the consequences. The calculated results are shown in the purple boxes.

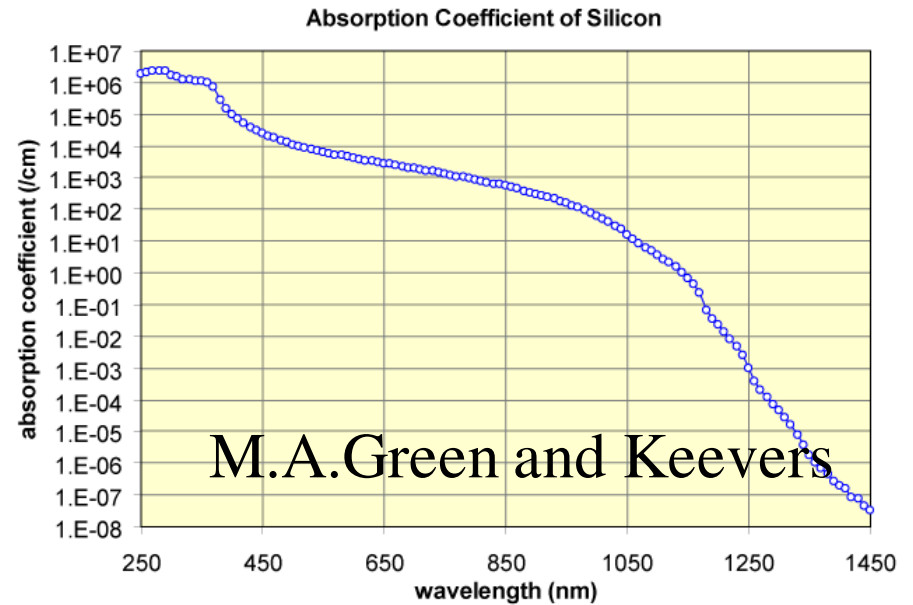
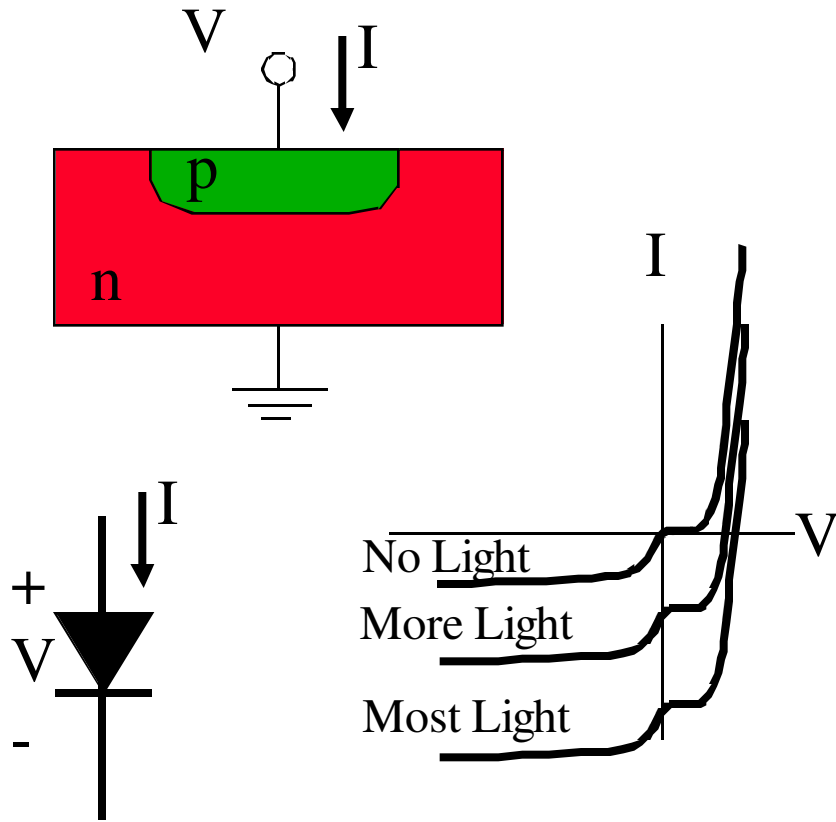
CONSTANTS		VARIABLES	
K	1.38E-23 J/K	Temp	<input type="text" value="300"/> K
q	1.60E-19 Coul	Nd =	<input type="text" value="1.00E+16"/> cm-3
Eg	1.12 eV	Na =	<input type="text" value="5.00E+14"/> cm-3
z0	8.85E-14 F/cm	ni	1.45E+10 cm-3
zr	11.7	Breakdown E	3.00E+05 V/cm
ni	1.45E+10 cm-3	Vr =	<input type="text" value="0"/> Volts Reverse Bias Voltage

CALCULATIONS:

$E_g = E_{g0} - (aT^2)/(T+B)$	1.075 eV
$n_i^2 = A T^3 e^{(-E_g/KT/q)}$	9.84E+20 cm-6
$KT/q =$	0.0259 Volts
$V_{bi} = (KT/q) \ln (N_a N_d / n_i^2)$	0.58 Volts
$W = [(2z_r/q)(V_{bi} + V_r)(1/N_a + 1/N_d)]^{0.5}$	1.25 μ m
$W_1 = W[N_d/(N_a + N_d)]$	1.19 μ m
$W_2 = W[N_a/(N_a + N_d)]$	0.06 μ m
$E_0 = -[(2q/\epsilon_0 \epsilon_r)(V_{bi} + V_a)(N_a N_d / (N_a + N_d))]^{0.5}$	-9.23E+03 V/cm
$C_j' = \epsilon_0 \epsilon_r / W$	8.26E-09 F/cm2

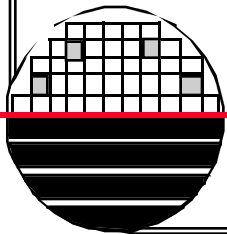


ADSORPTION VERSUS DISTANCE



$$\phi(x) = \phi(0) \exp^{-\alpha x}$$

Find % adsorbed for Green light at $x=5 \mu\text{m}$ and Red light at $5 \mu\text{m}$



CHARGE GENERATION vs WAVELENGTH

$$E = h\nu = hc / \lambda$$

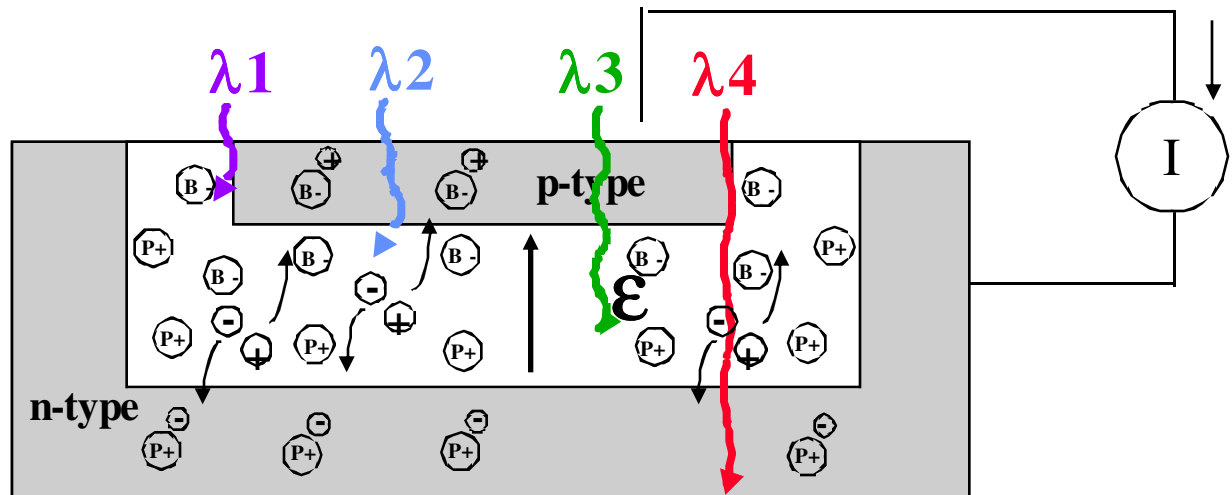
$$h = 6.625 \text{ e-34 j/s}$$

$$= (6.625 \text{ e-34}/1.6\text{e-19}) \text{ eV/s}$$

$$E = 1.55 \text{ eV (red)}$$

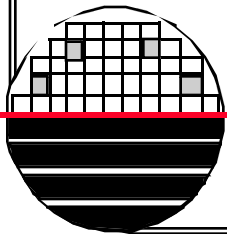
$$E = 2.50 \text{ eV (green)}$$

$$E = 4.14 \text{ eV (blue)}$$

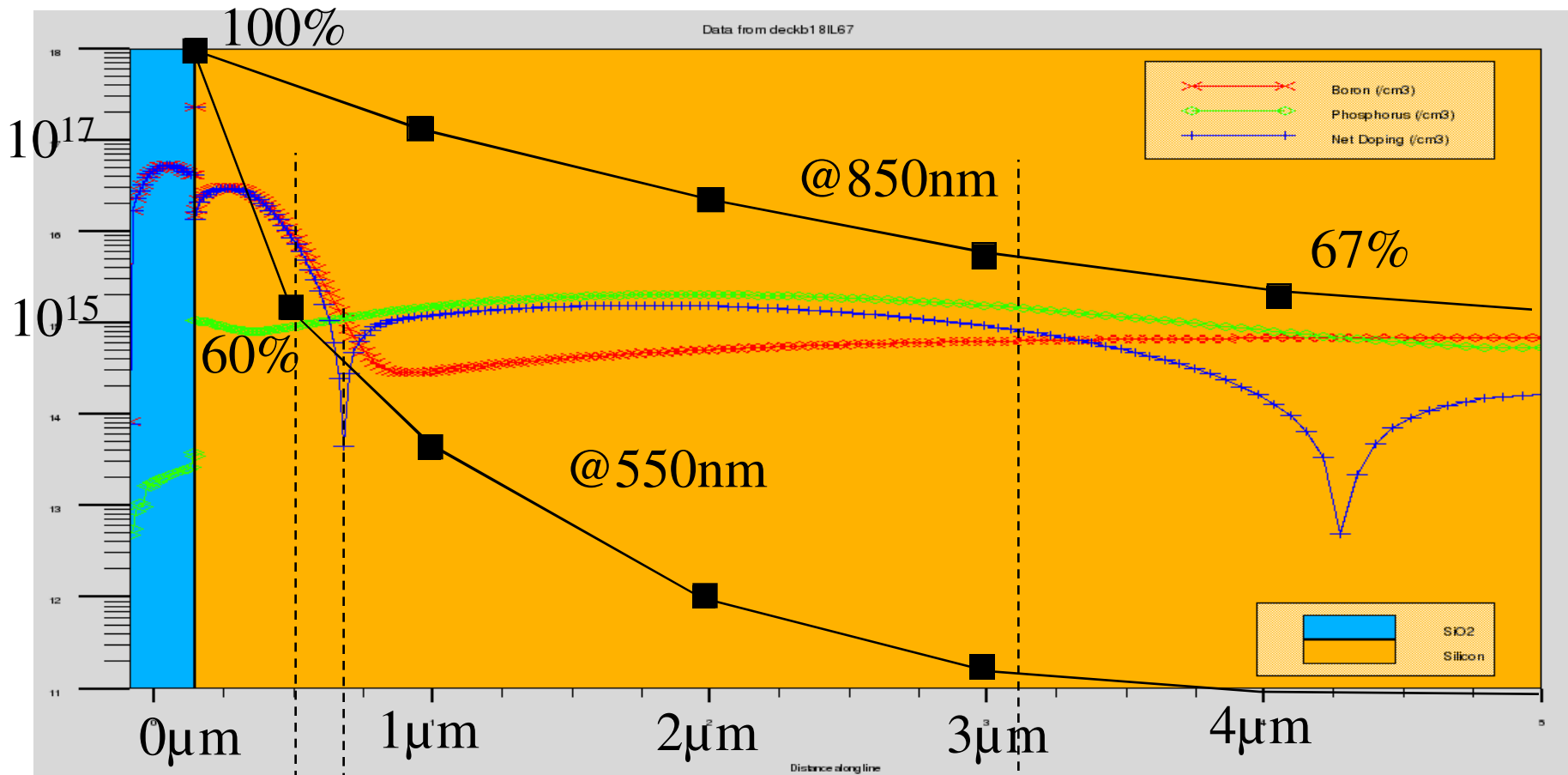


To generate e-h pair in silicon we need $E \geq E_{\text{gap}}$

$$E \geq 1.12 \text{ eV}$$



PN JUNCTION DESIGN FOR PHOTO DIODE



Space Charge Layer

CHARGE GENERATION IN SEMICONDUCTORS

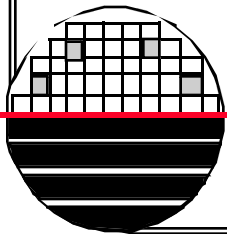
$$E = h\nu = hc / \lambda$$

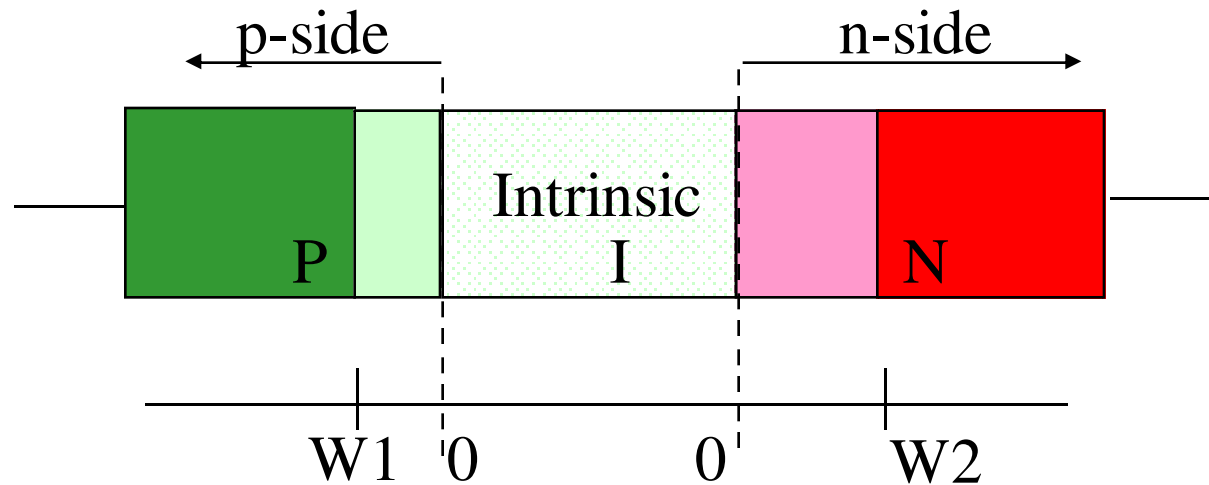
What wavelengths will not generate e-h pairs in silicon. Thus silicon is transparent or light of this wavelength or longer is not adsorbed?

From: Micromachined Transducers, Gregory T.A. Kovacs

Semiconductor	Bandgap (eV) 300 K	Bandgap (eV) 0 K	λ_{max} (μm) 300 K
BN	7.500	-	0.165
C	5.470	5.480	0.227
ZnS	3.680	3.840	0.337
GaN	3.360	3.500	0.369
ZnO	3.350	3.420	0.370
Alpha-SiC	2.996	3.030	0.414
CdS	2.420	2.560	0.512
GaP	2.260	2.340	0.549
BP	2.000	-	0.620
CdSe	1.700	1.850	0.729
AlSb	1.580	1.680	0.785
CdTe	1.560	-	0.795
GaAs	1.420	1.520	0.873
InP	1.350	1.420	0.919
Si	1.120	1.170	1.107
GaSb	0.720	0.810	1.722
Ge	0.660	0.740	1.879
PbS	0.410	0.286	3.024
InAs	0.360	0.420	3.444
PbTe	0.310	0.190	4.000
InSb	0.170	0.230	7.294
Sn	-	0.082	15.122 @ 0 K

Table of various semiconductors in order of increasing λ_{max} . From Sze (1981).



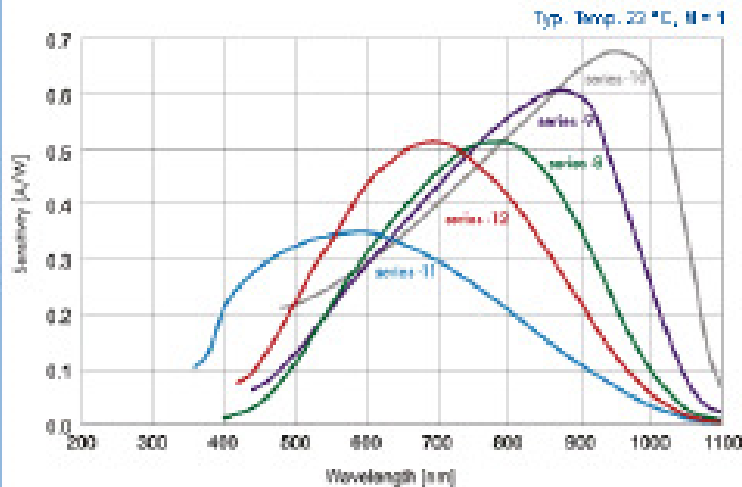
PIN, AVALANCE PHOTODIODES (APD)

PIN and Avalanche photo diodes (APD) are made with an intrinsic (almost zero doping) layer between the N and P layers. The depletion layer is increased by the width of the Intrinsic layer. Avalanche diodes are the same structure but used with large reverse bias (>100 volts) that creates large electric field in the space charge layer that can accelerate the electrons to velocities high enough to cause ionizing collisions giving a multiplication of carriers. Each photon can generate hundreds of electron hole pairs.

PIN, AVALANCHE PHOTODIODES (APD)

Si Avalanche Photodiodes (APD)

Spectral Sensitivity



Are high speed, high sensitivity photodiodes with an internal gain mechanism and high gain bandwidth product with a spectral response range between 300 nm and 1100 nm



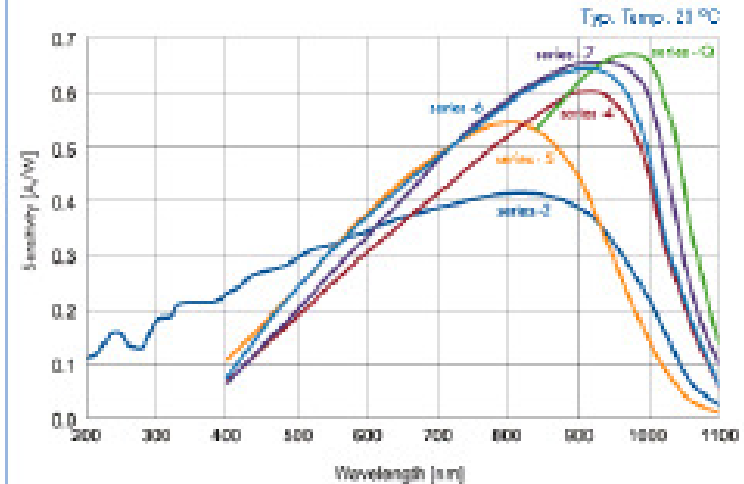
Position Sensing Photodiodes (PSD)

Single and Dual-Axis PSD's with high position resolution and high linearity



Si PIN Photodiodes

Spectral Sensitivity

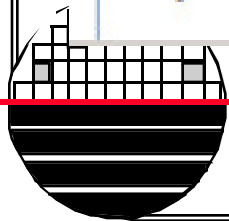


Optimised for high UV-response, low dark current, high shunt resistance, very low capacitance, etc. Ideal for high performance and standard applications like x-ray detection, scintillation detectors and more... Spectral response range between 190nm and 1100nm.



Quadrant Photodiodes

Small Gap, excellent uniformity, low dark current, high shunt resistance, high resolution



PHOTOMULTIPLIER

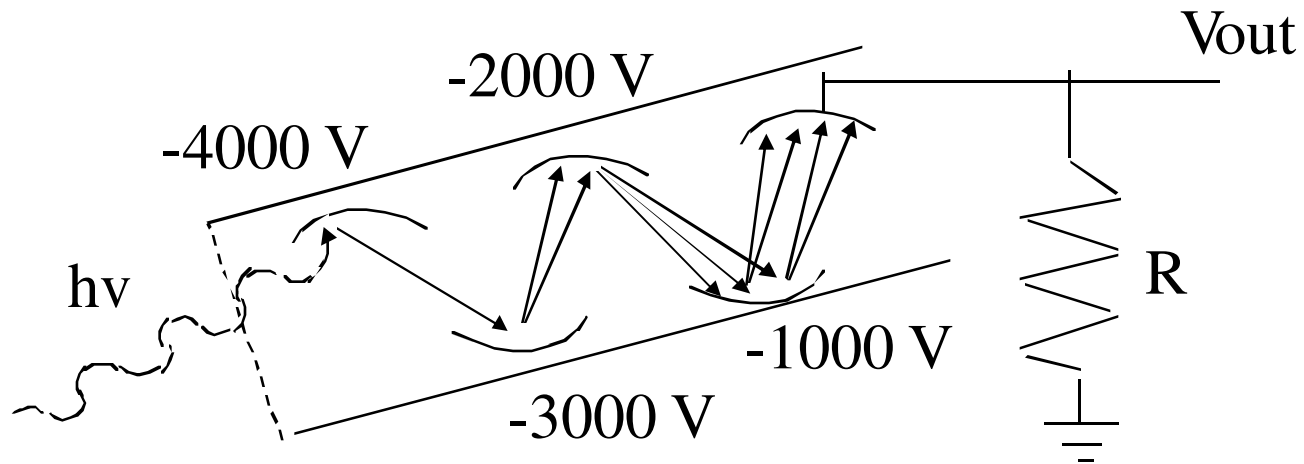
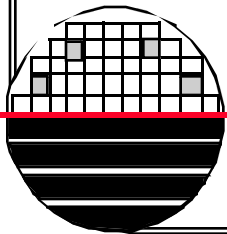


Photo Multiplier Tube (low work Function)



CHARGE COLLECTION IN MOS STRUCTURES

$$E = h\nu = hc / \lambda$$

$$h = 6.625 \times 10^{-34} \text{ j/s}$$

$$= (6.625 \times 10^{-34} / 1.6 \times 10^{-19}) \text{ eV/s}$$

- E = 1.55 eV (red)
- E = 2.50 eV (green)
- E = 4.14 eV (blue)

electron
and hole
pair

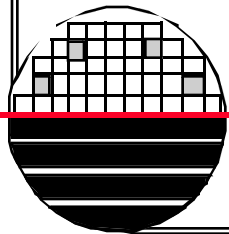
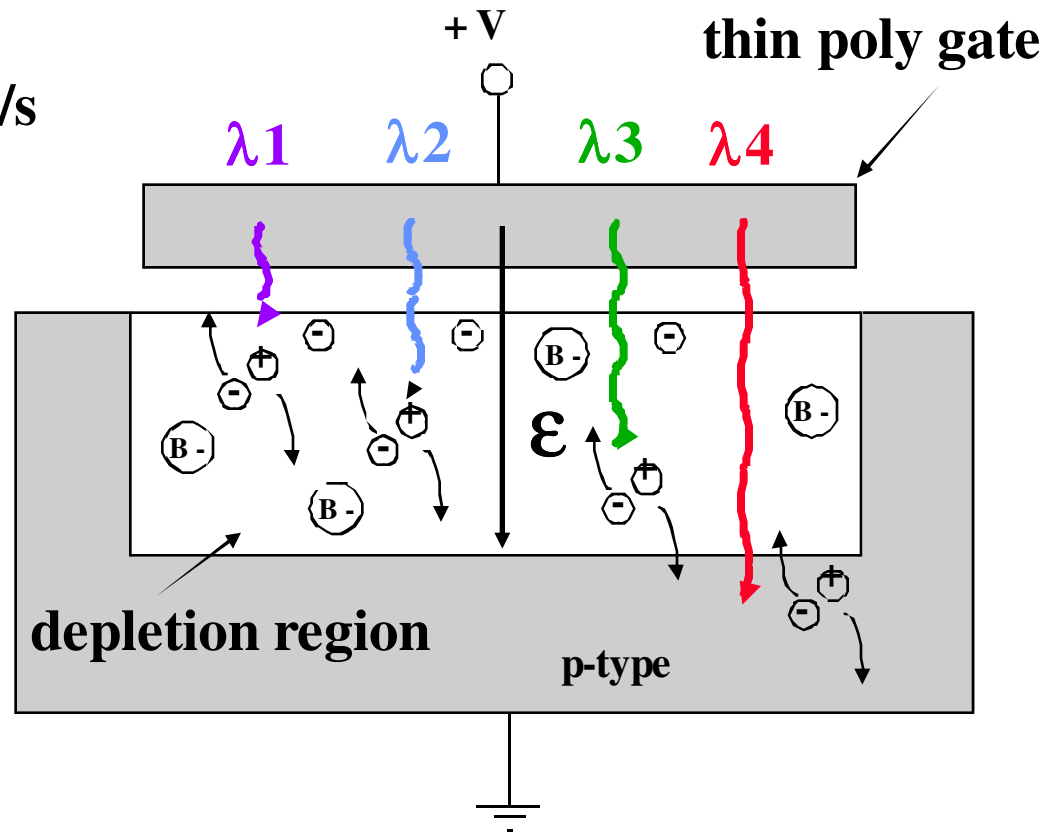


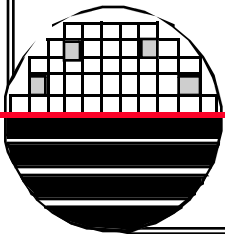
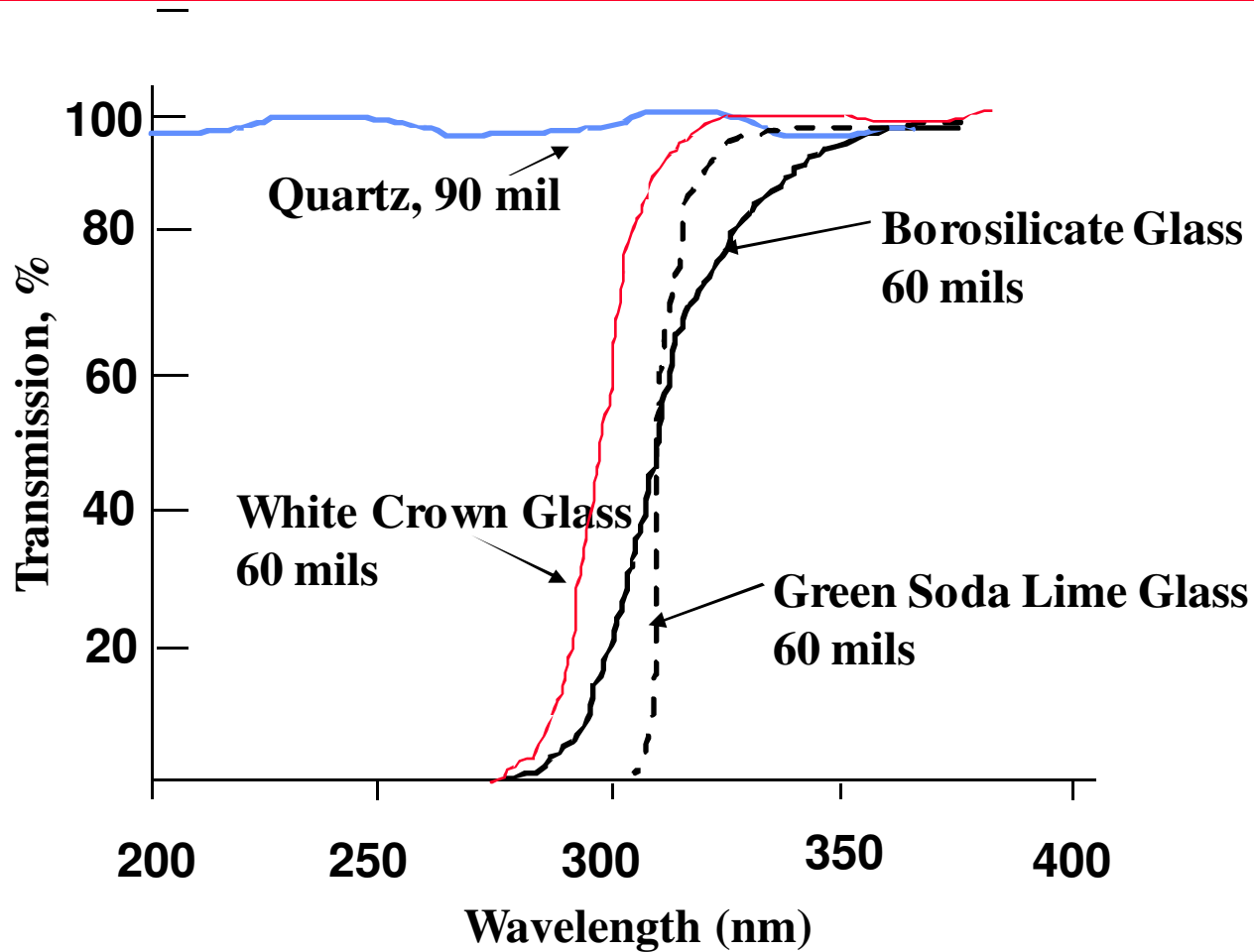
PHOTO DETECTORS

From: Micromachined Transducers, Gregory T.A. Kovacs

Device Type	Gain	Response Time (s)	Typical Temperature
Photomultiplier	$> 10^6$	10^{-7} to 10^{-9}	300 (sometimes cooled)
Photoconductor	1 to 10^6	10^{-3} to 10^{-8}	4.2 to 300
Metal-Semiconductor-Metal Photodetector	1 or less	10^{-10} to 10^{-12}	300
p-n Photodiode	1 or less	10^{-6} to 10^{-11}	300 (sometimes cooled to 77 K)
p-i-n Photodiode	1 or less	10^{-6} to 10^{-9}	300
Metal-Semiconductor Diode	1 or less	10^{-9} to 10^{-12}	300
Avalanche Diode	10^2 to 10^4	10^{-10}	300
Bipolar Phototransistor	10^2	10^{-6} to 10^{-8}	300
Bipolar Photo-Darlington	10^4	10^{-5} to 10^{-6}	300
Field-Effect Phototransistor	10	10^{-7}	300
CCD Cell (Metal-Insulator-Semiconductor Capacitor)	1 or less	10^{-5} to 10^{-8}	300 (sometimes cooled)

Ro Gains and response times of some typical photodetectors (some are optimistic!).
Mi After Sze (1981). Note that the CCD cell, and some extrinsic photoconductors, are integrating detectors, and thus the response time figures can be somewhat misleading.

TRANSMISSION PROPERTIES OF OPTICAL GLASS



SOLAR CELL TUTORIAL

SOME TERMS AND DEFINITIONS:

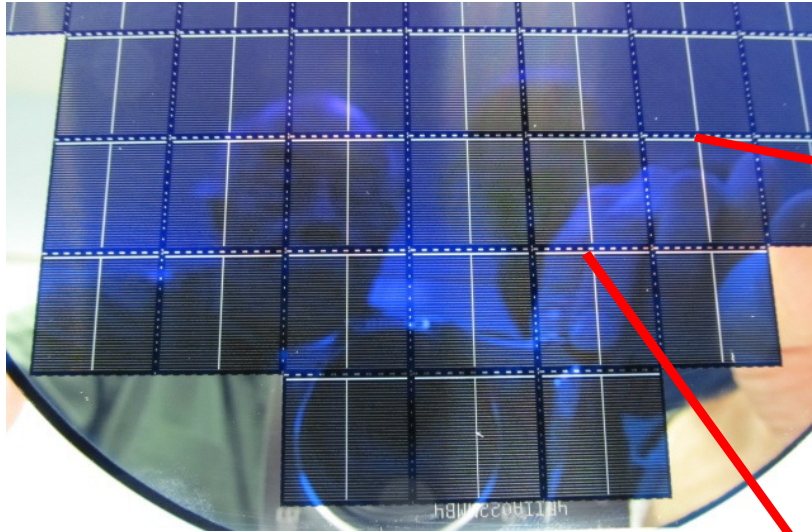
Air Mass – amount of air between sun and solar cell. In space $AM=0$ at the equator at noon $AM=1$, if the sun is arriving at an angle θ , $AM=1/\cos \theta$. $AM1.5$ is the standard for most solar cell work in USA and gives a sum total of $1000\text{w}/\text{m}^2$ over the entire spectrum of wavelengths from $0.2\mu\text{m}$ to $2.0\mu\text{m}$

Efficiency is the ratio of the power out of a solar cell to the power falling on the solar cell (normally $1000\text{w}/\text{m}^2$ with the $AM1.5$ spectrum) Since Si solar cells can not absorb much of the infrared spectrum from the sun, and other factors, typical efficiencies are limited to 26-29% for basic silicon solar cells.

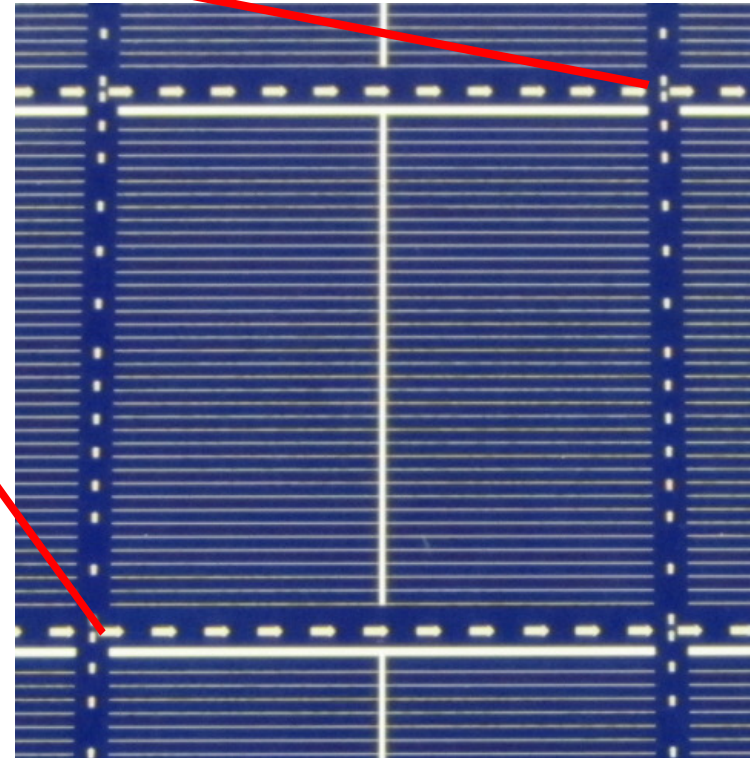
Quantum Efficiency – normalized ratio of electrons and holes collected to photons incident on the cell at a single wavelength, given in %.

FF – Fill Factor, a figure of merit, the “squareness “ of the diode I-V characteristic in 4th quadrant with light falling on the cell.

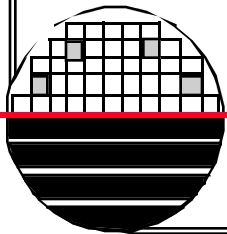
SOLAR CELL



16000um x 16000um

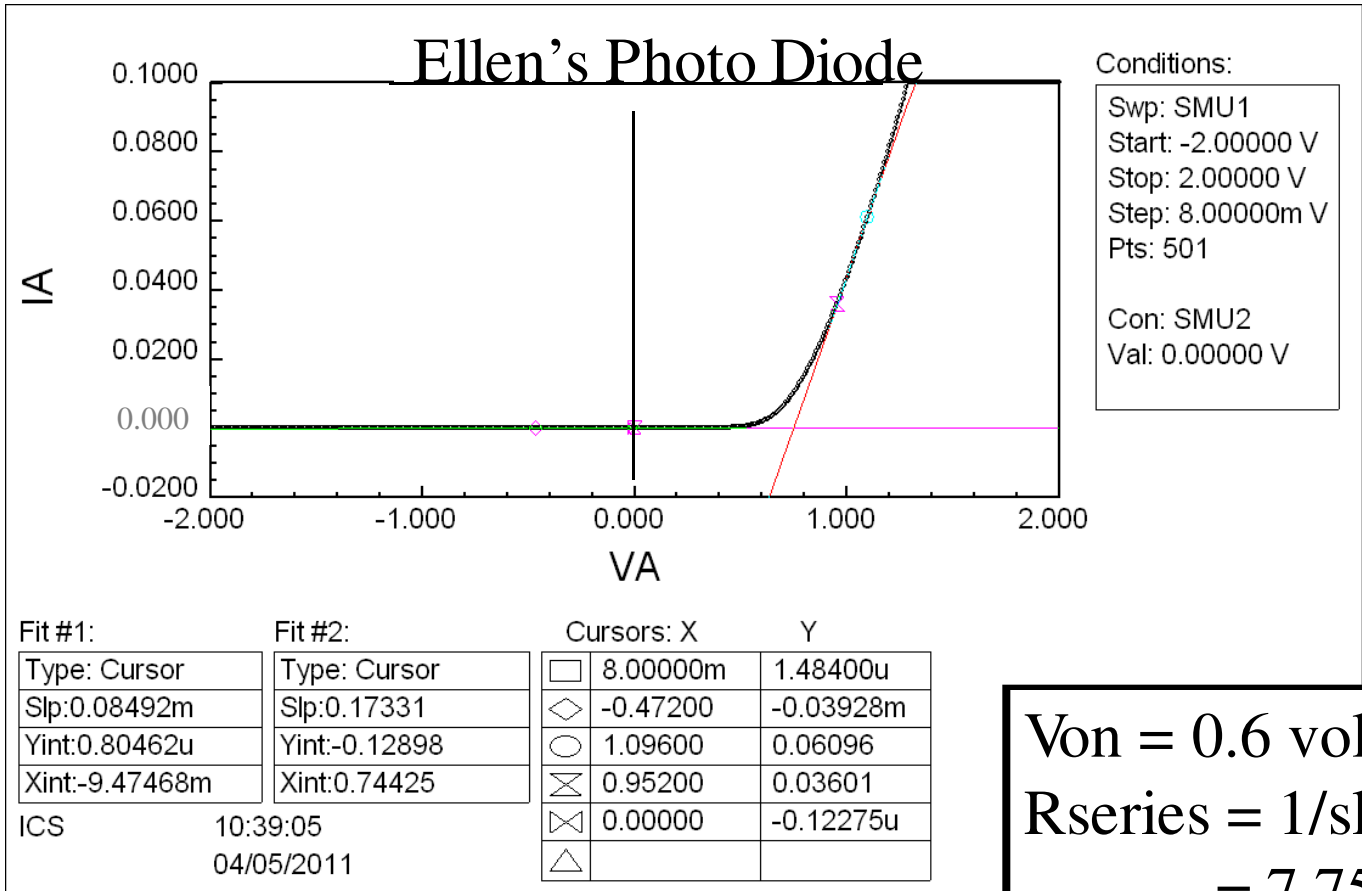


Ellen Sedlack 2011

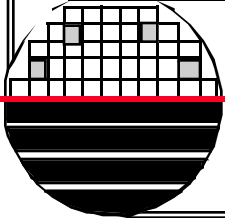


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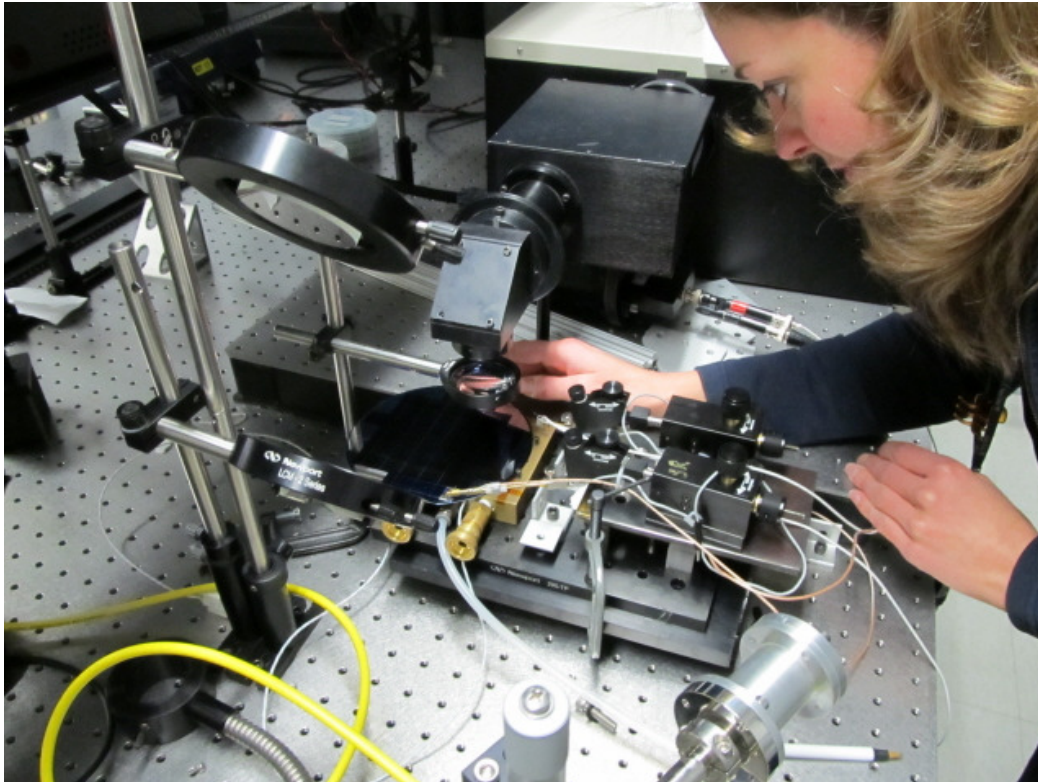
I-V CHARACTERISTICS OF SOLAR CELL



$V_{on} = 0.6 \text{ volts}$
 $R_{series} = 1/\text{slope} = 1/0.129$
 $= 7.75 \text{ ohms}$
 $I_s = 1.48 \mu\text{A (in room light)}$

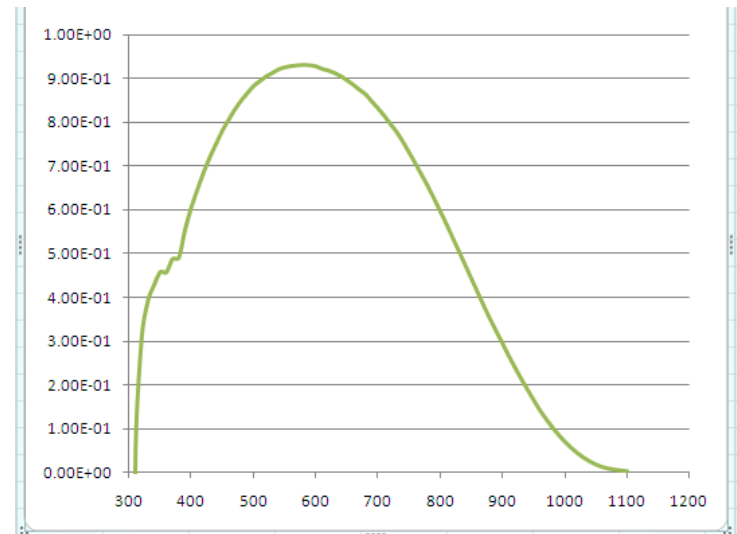


SOLAR CELL - QUANTUM EFFICIENCY

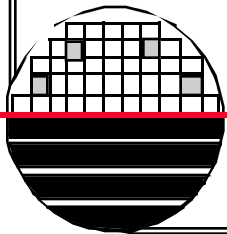


Ellen Sedlack 2011

93% between 550nm and 650nm

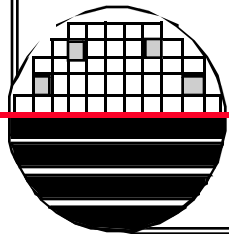
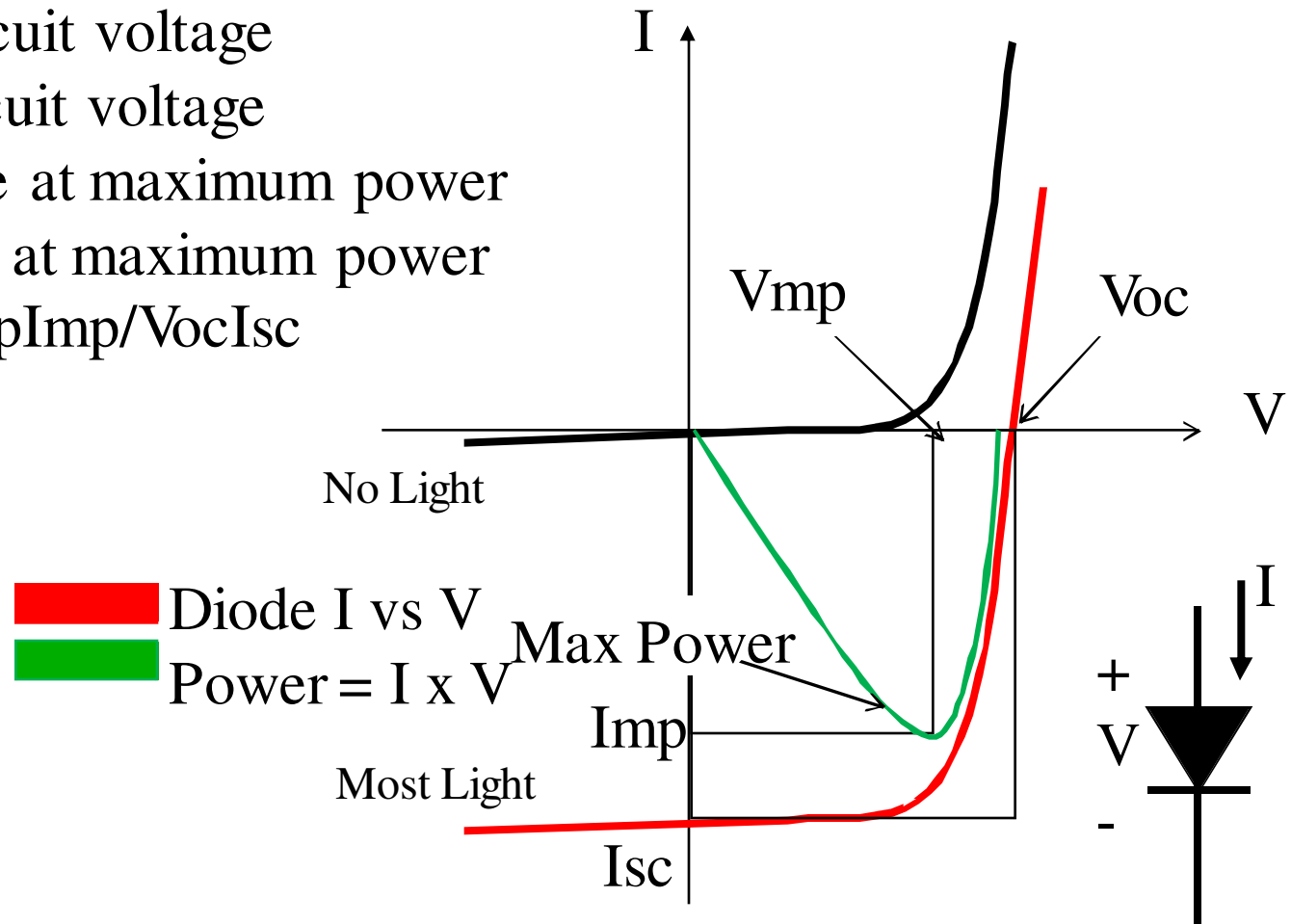


Yushuai Dai



SOLAR CELL TUTORIAL

- Voc** - open circuit voltage
- Isc** – short circuit current
- Vmp** – Voltage at maximum power
- Imp** – Current at maximum power
- FF** – $FF = V_{mp}I_{mp}/V_{oc}I_{sc}$



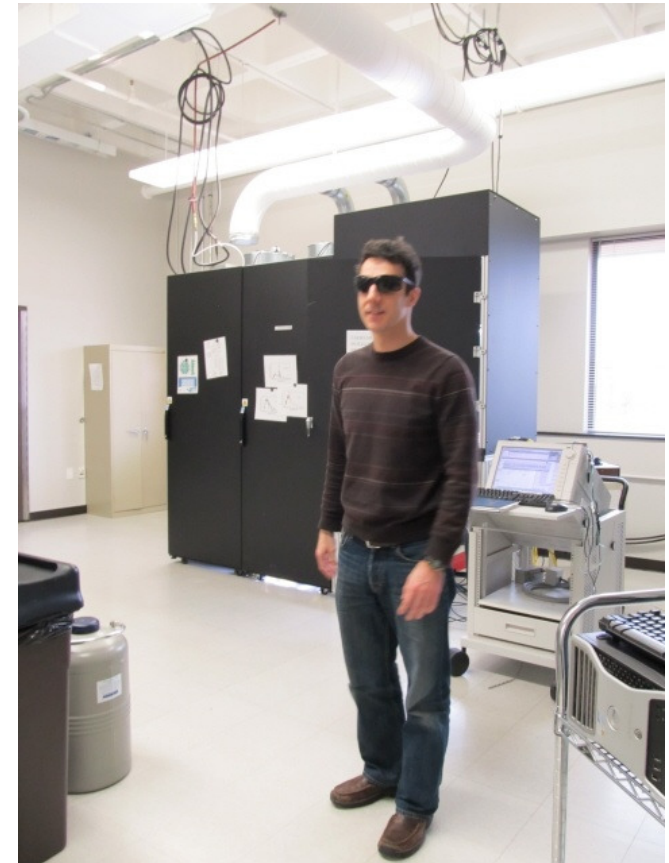
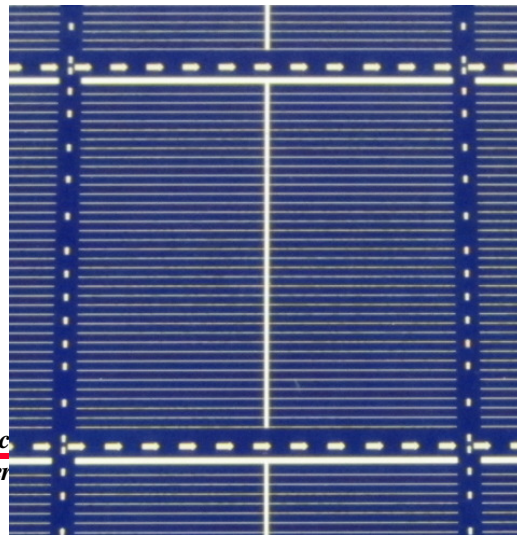
SOLAR CELL – POWER EFFICIENCY

AM 1.5 Light Source



Zachary Bittner

*Rochester Institute of Tec
Microelectronic Engineer*

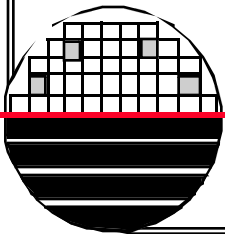
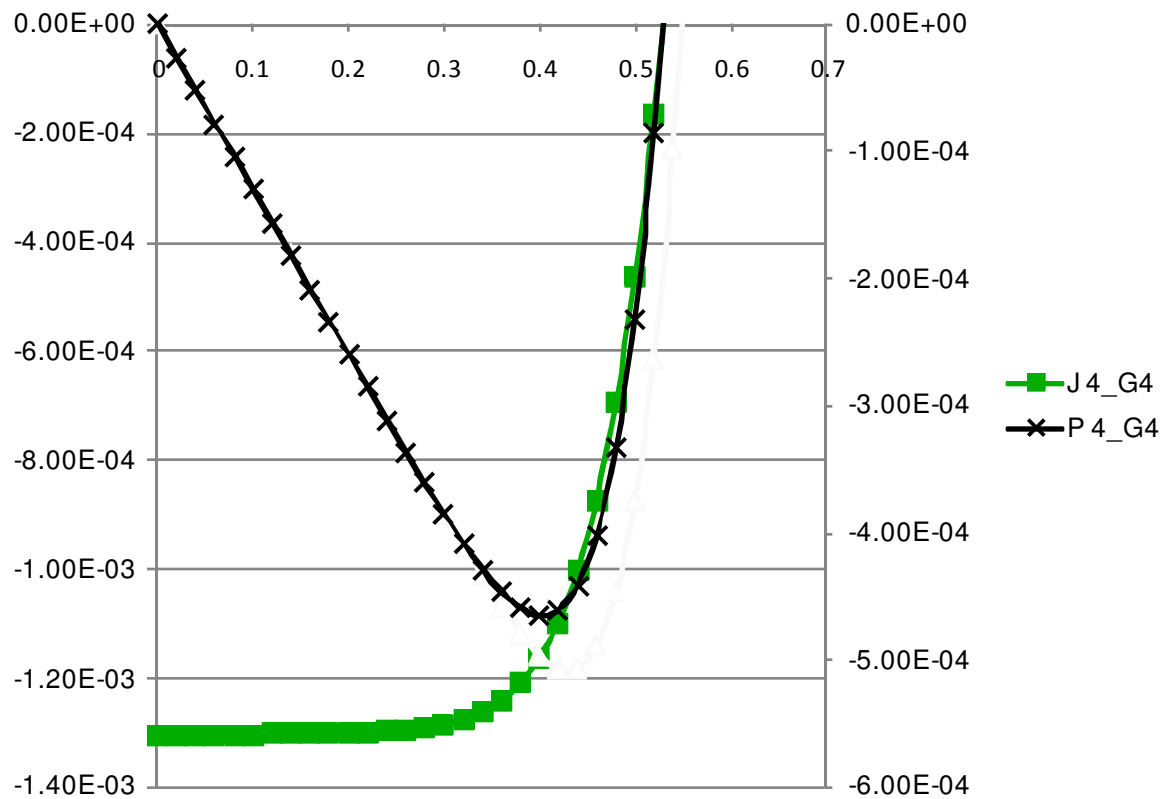


Ivan
Puchades

POWER, EFFICIENCY, I_{sc} , V_{oc}

Setting	Spot size (mm)	Cell size (cm)	Current (A)	J (A/cm ²)	Irradiance (mW/cm ²)
2.25x @max	1.267	0.25	2.77E-04	1.11E-03	3.39

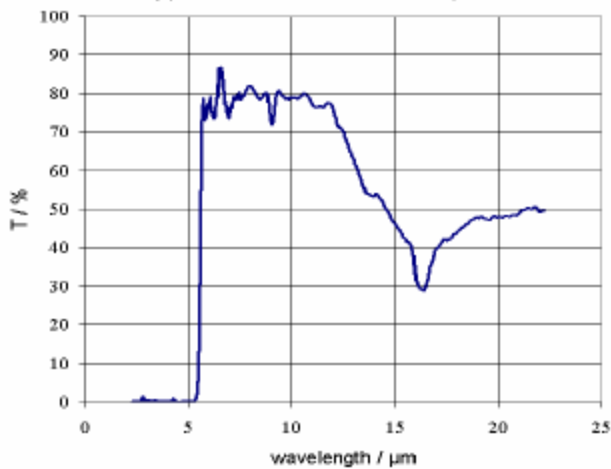
Column1	P 4_G5	P 4_G4
Pmax	-5.06E-04	-4.65E-04
Jmax	-1.21E-03	-1.160E-03
Vmax	0.42	0.380
Jsc	-1.30E-03	-1.30E-03
Voc	5.60E-01	0.540
FF	69.8%	62.8%
efficiency	-15%	-14%



THERMOPILE SENSOR



Typical Transmission 5.5µm Filter

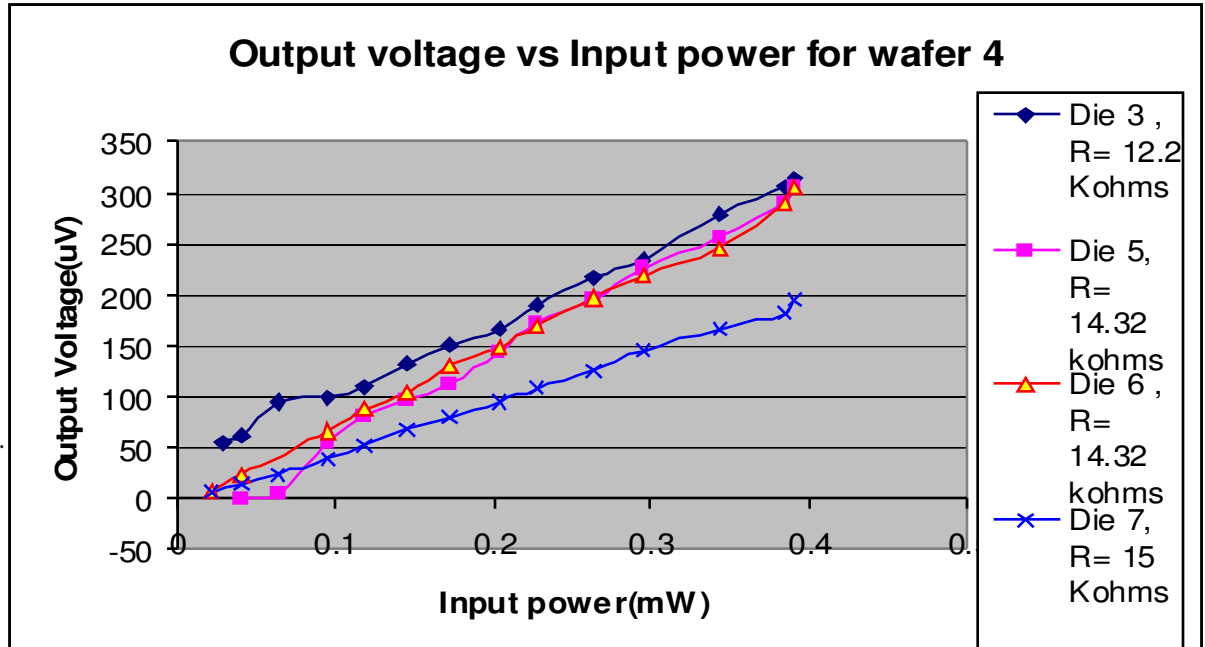
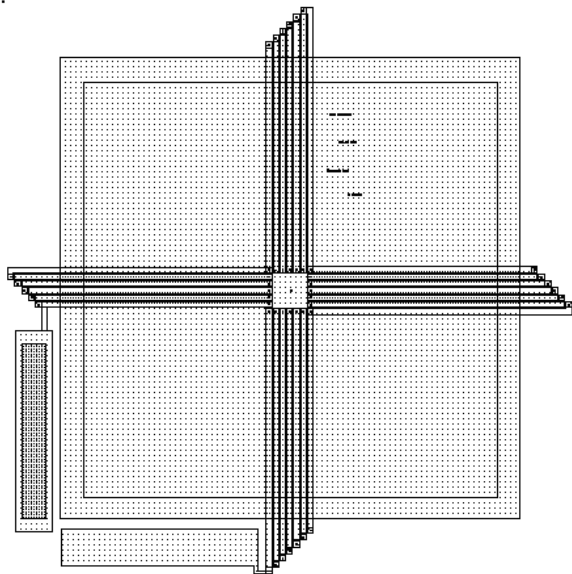
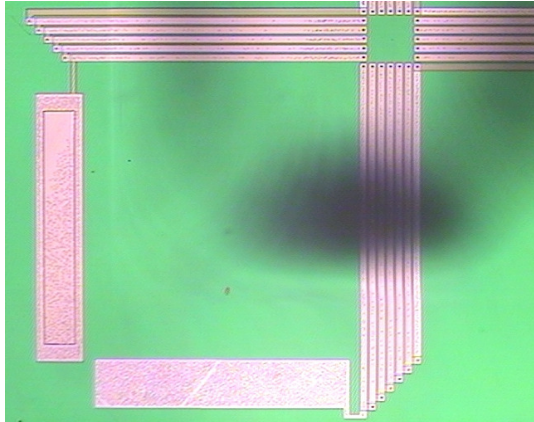


HMS Z11 – F5.5

Thermopile				
Parameter	Typical Value	Unit	Condition	Remark
Element Size	0.6 x 0.6	mm ²		Active area
Voltage Response	13	Vmm ² /W		
Sensitivity	36	V/W	Tobj=373K Tamb=298K	
Thermopile Resistance	86	kΩ	25°C	
TC of Thermopile Resistance	20	ppm	Operating temp. range	
Thermopile Noise	38	nV/√Hz	25°C	
Detectivity	5.6 · 10 ⁷	cm√Hz/W		
Time Constant	<6	ms	63%	

www.heimannsensor.com

RIT THERMOPILE SENSOR



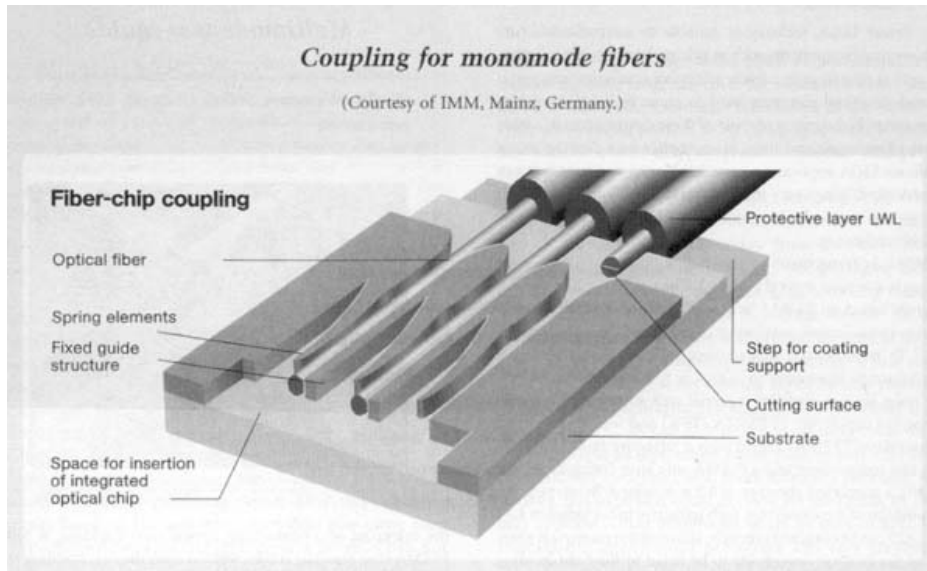
Usha Kuppuswamy, 2005

chnology
ring

FIBER OPTIC COMPONENTS

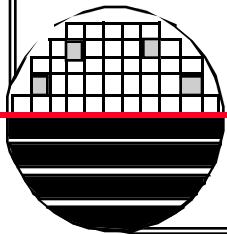
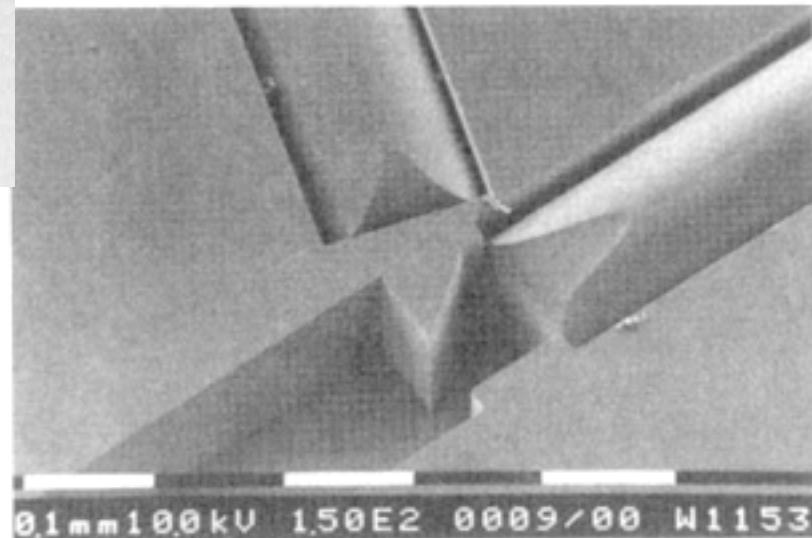
Coupling for monomode fibers

(Courtesy of IMM, Mainz, Germany.)

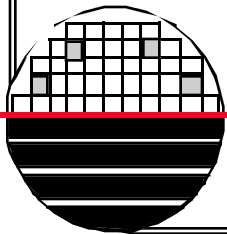
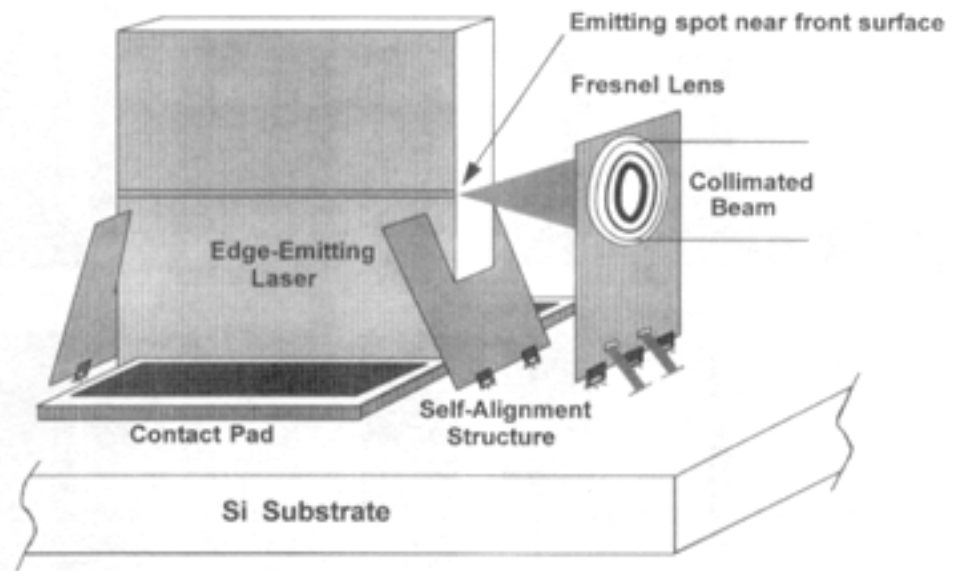
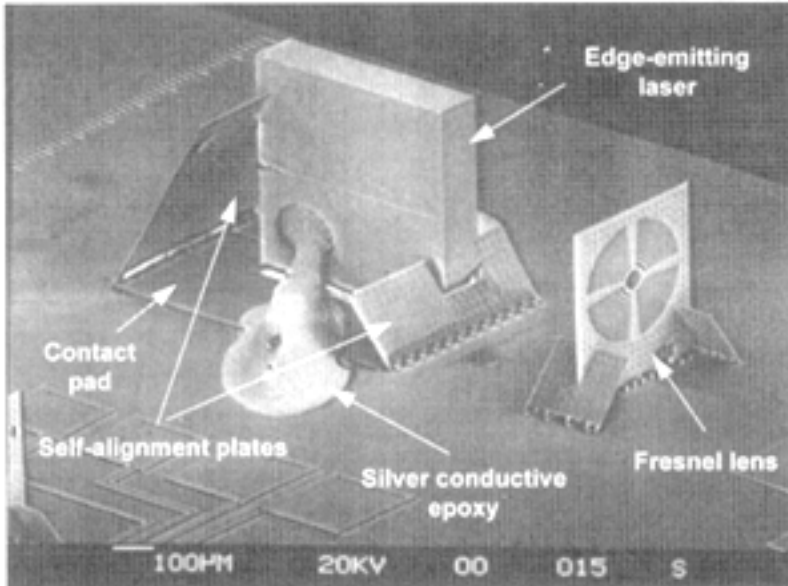


*Fiber coupling
(1 × 2 beam splitter)*

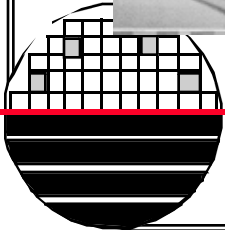
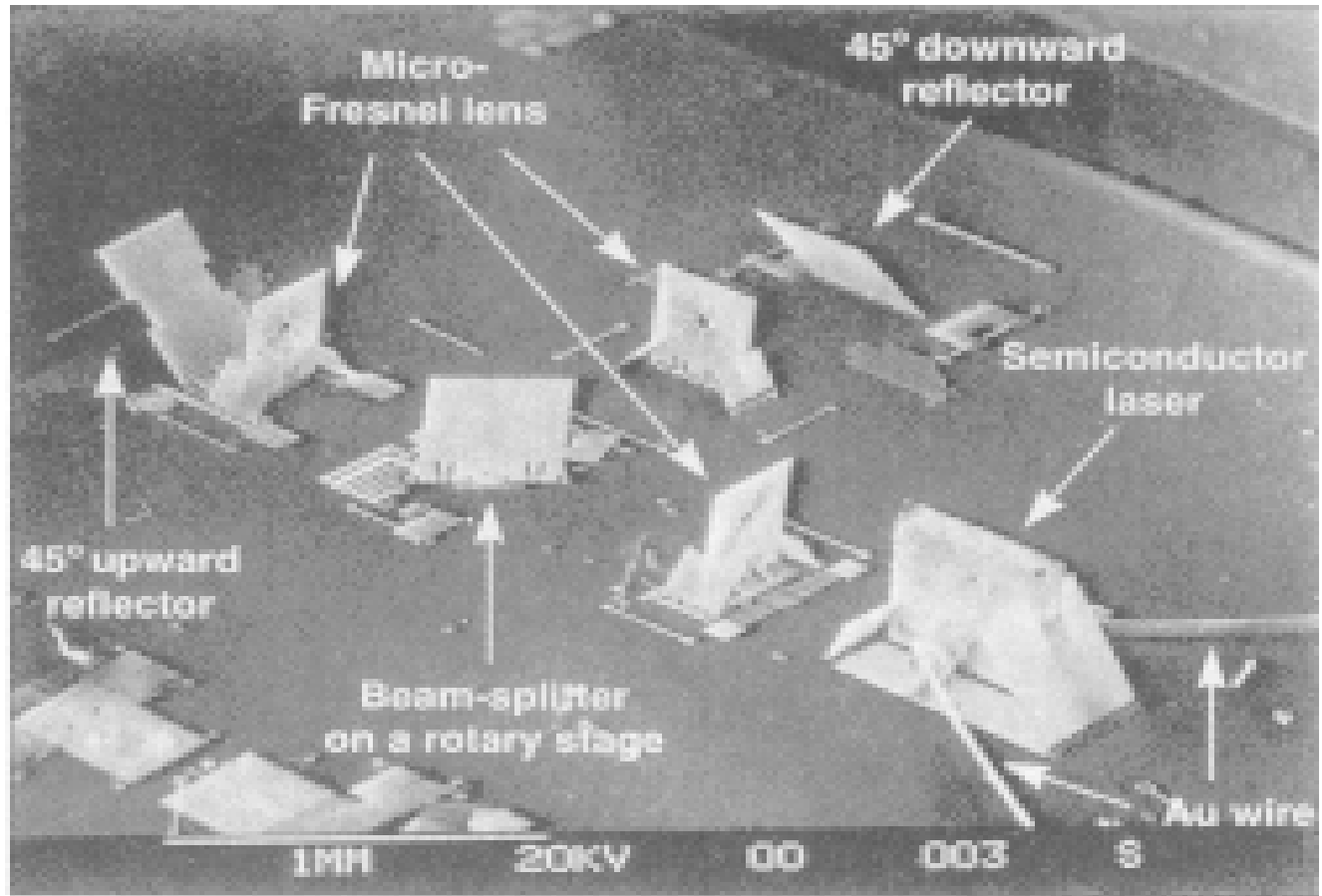
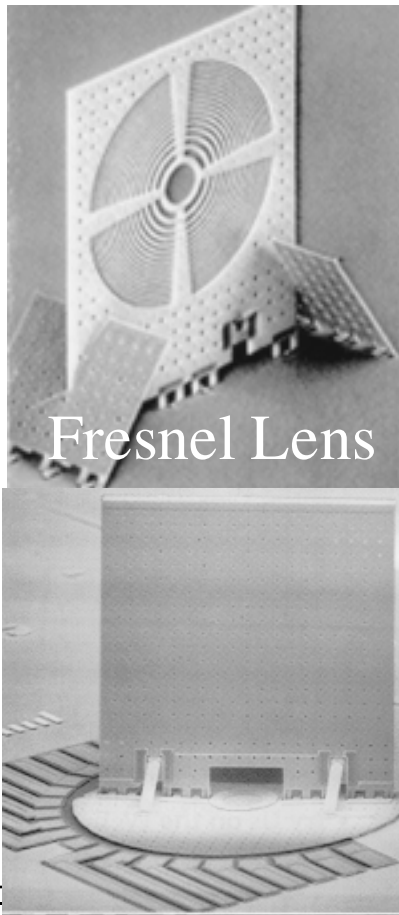
(Courtesy, KfK, Karlsruhe, Germany.)



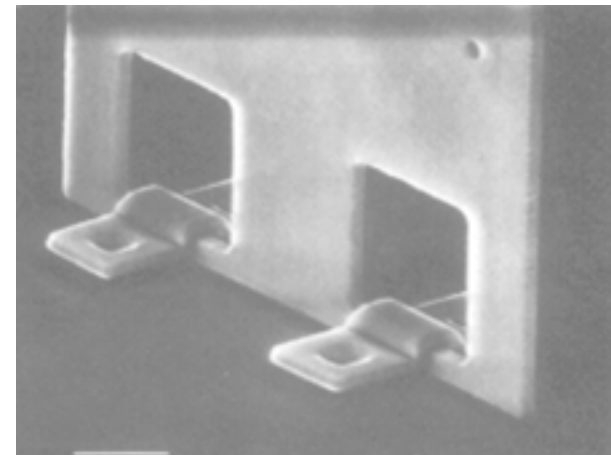
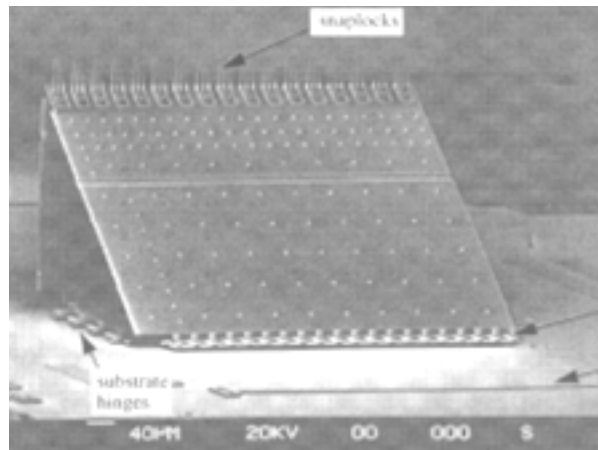
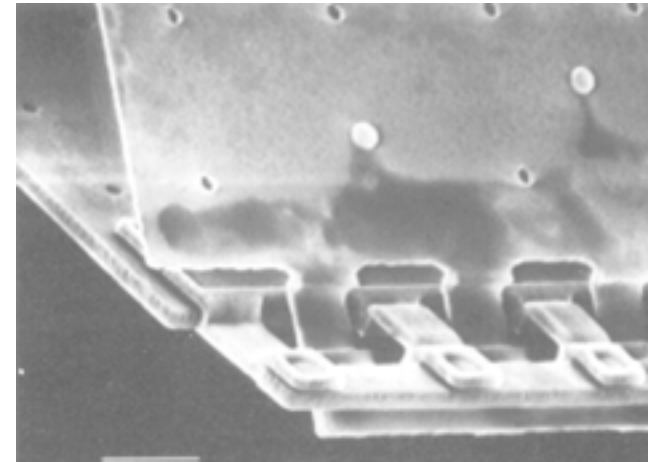
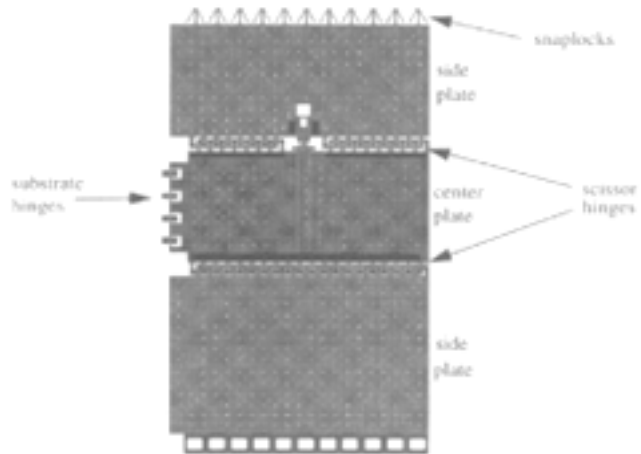
LASER AND FRESNEL LENS



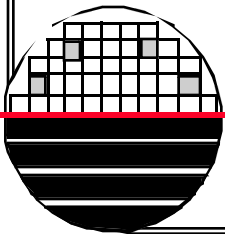
OPTICAL SYSTEM



HINDGE



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SELF ASSEMBLY

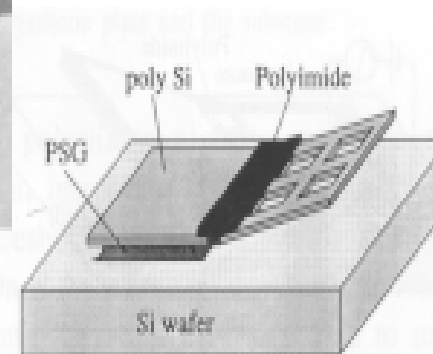
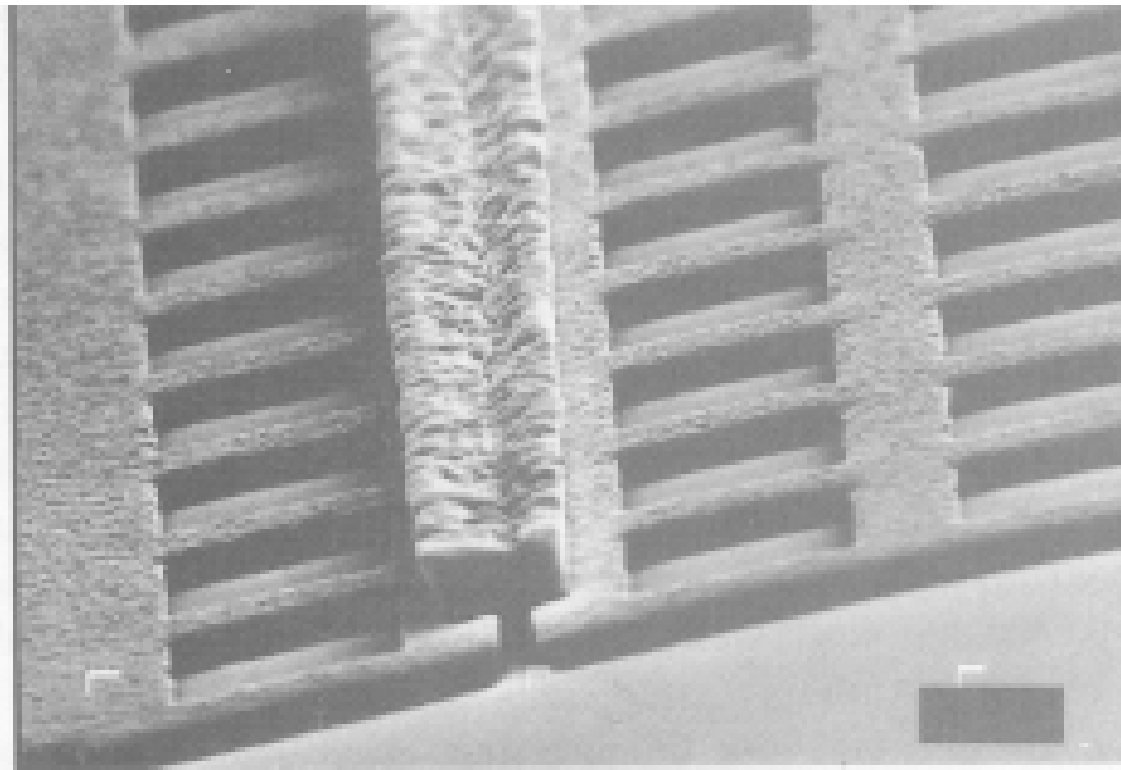
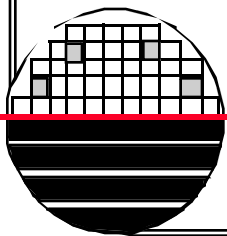
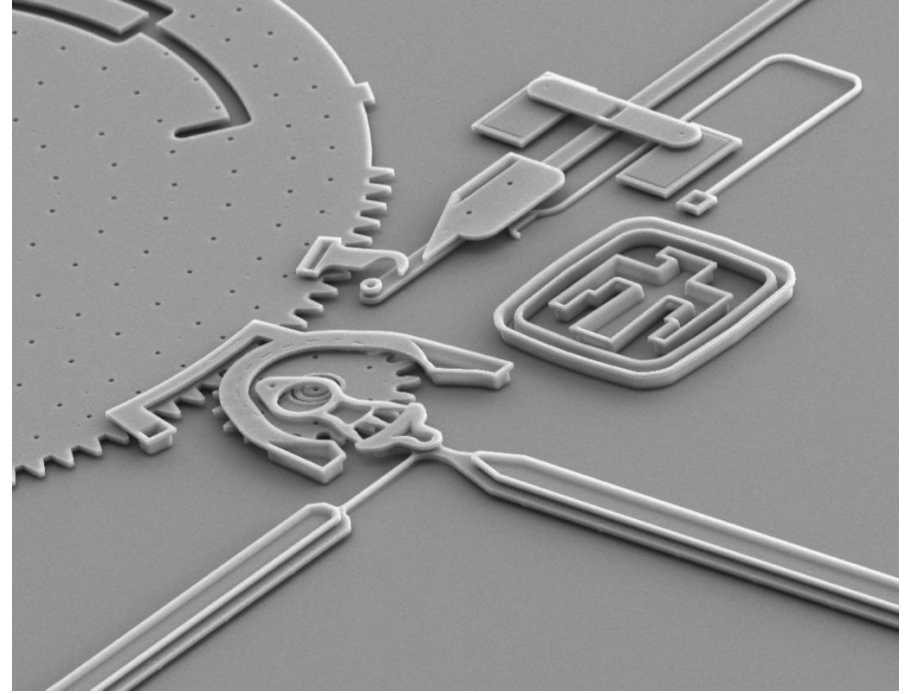
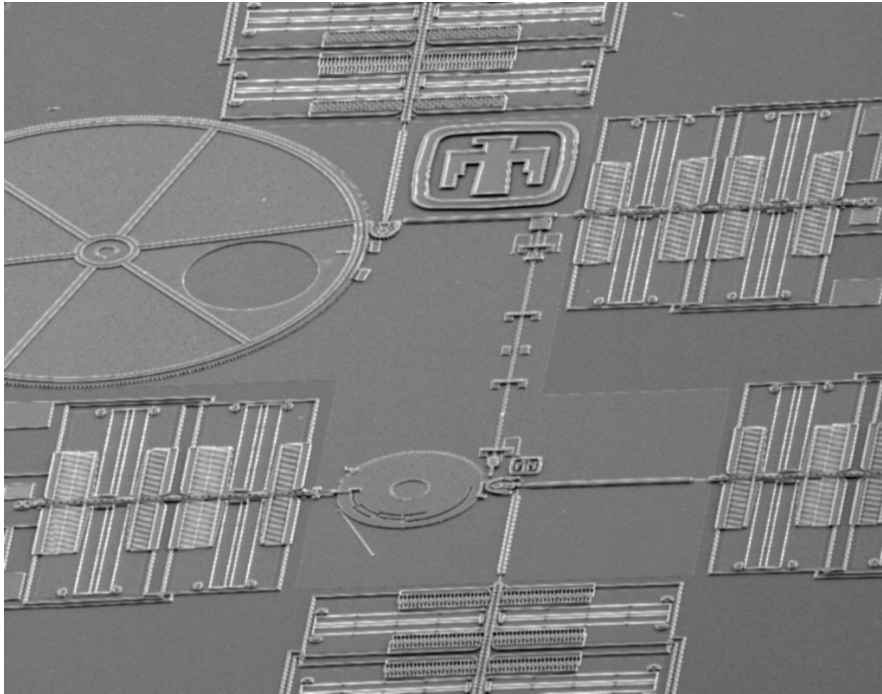


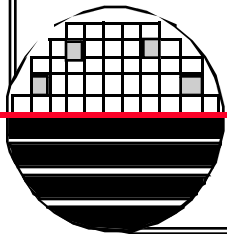
Fig. 2. Basic model of the external skeleton. Three-dimensional structure is constructed by bending along the polyimide hinges.



ELECTROSTATIC COMB DRIVE

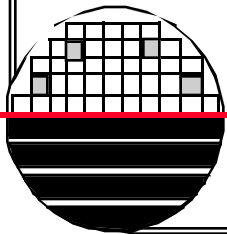
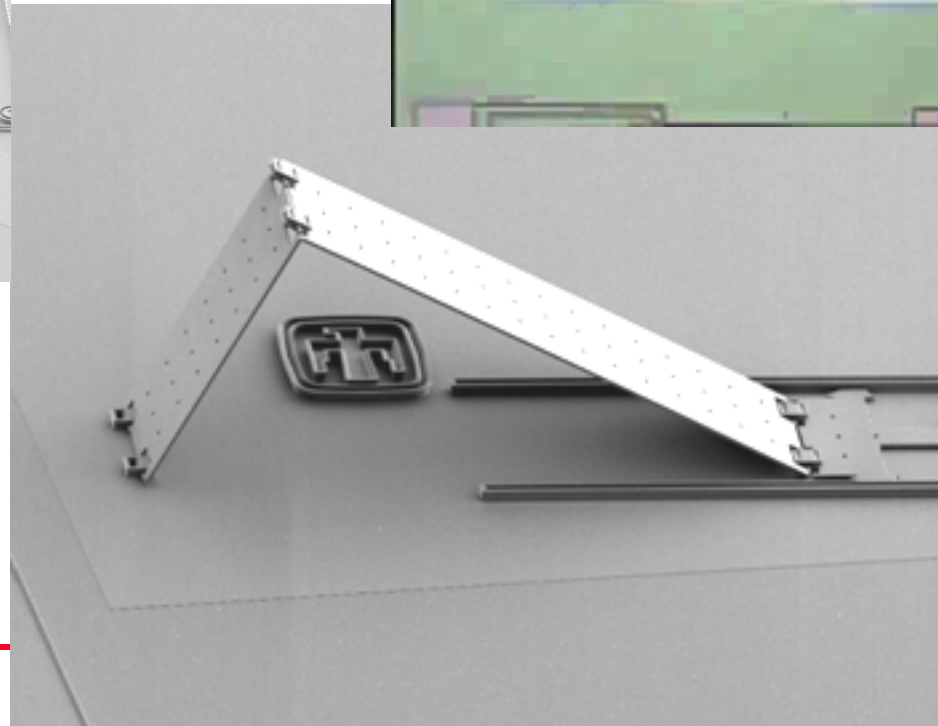
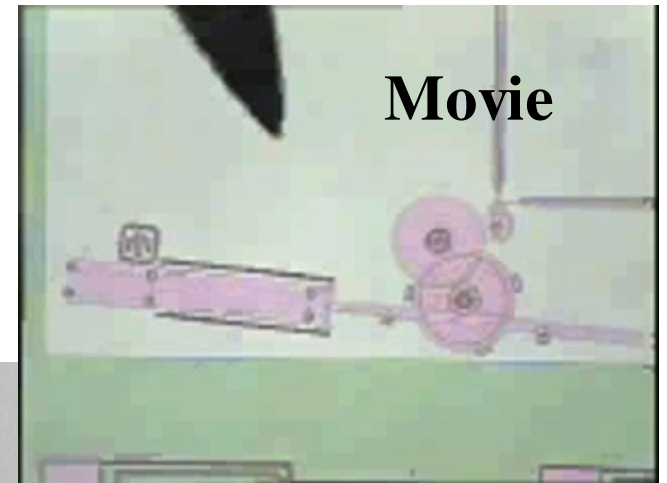
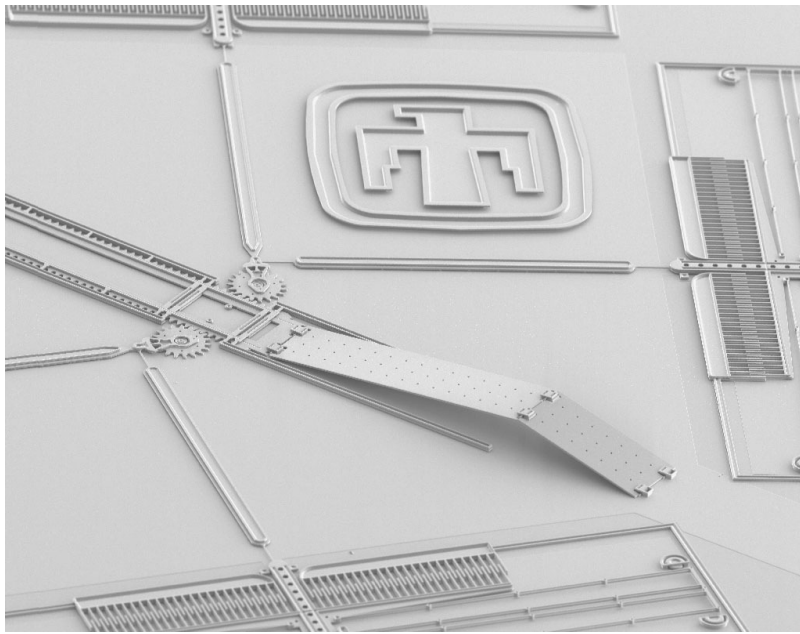


Movies at www.sandia.gov



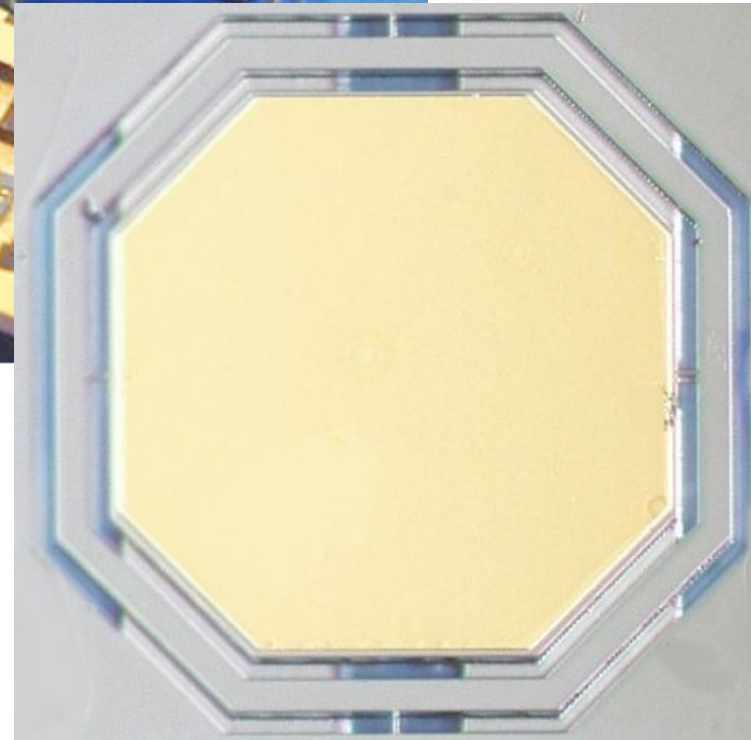
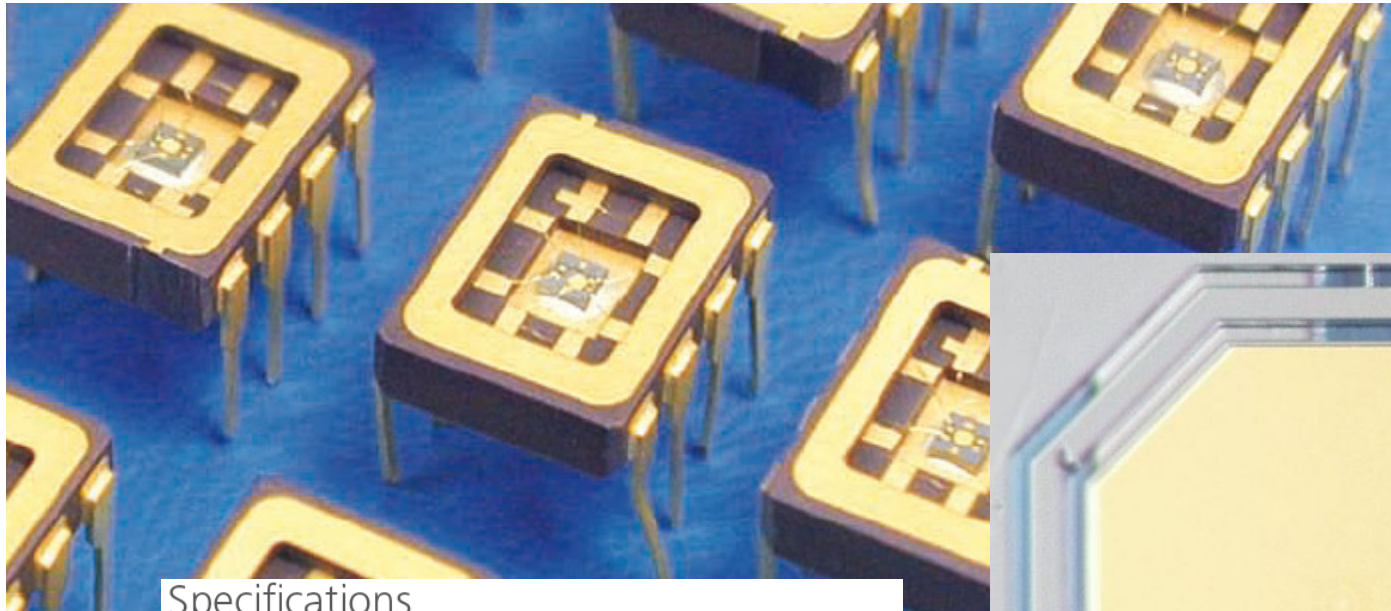
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Microelectronic Engineering*

ELECTROSTATIC COMB DRIVE MIRROR



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ELECTROSTATIC MIRROR



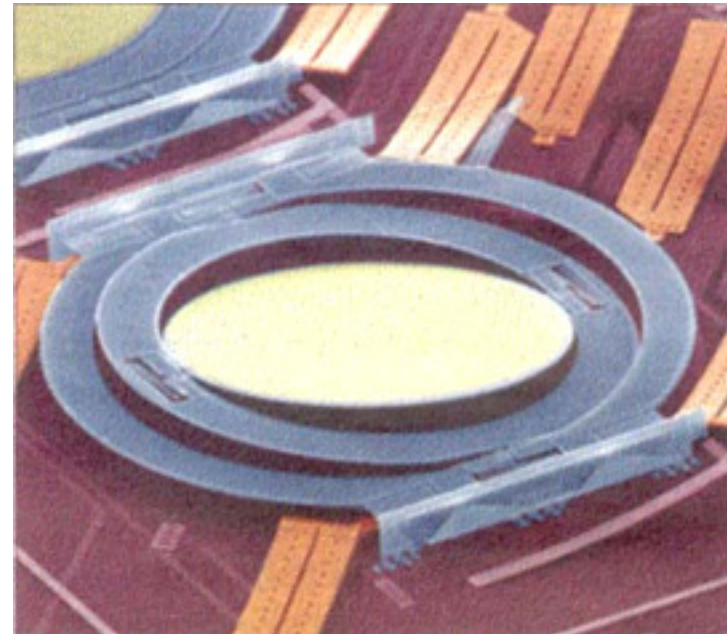
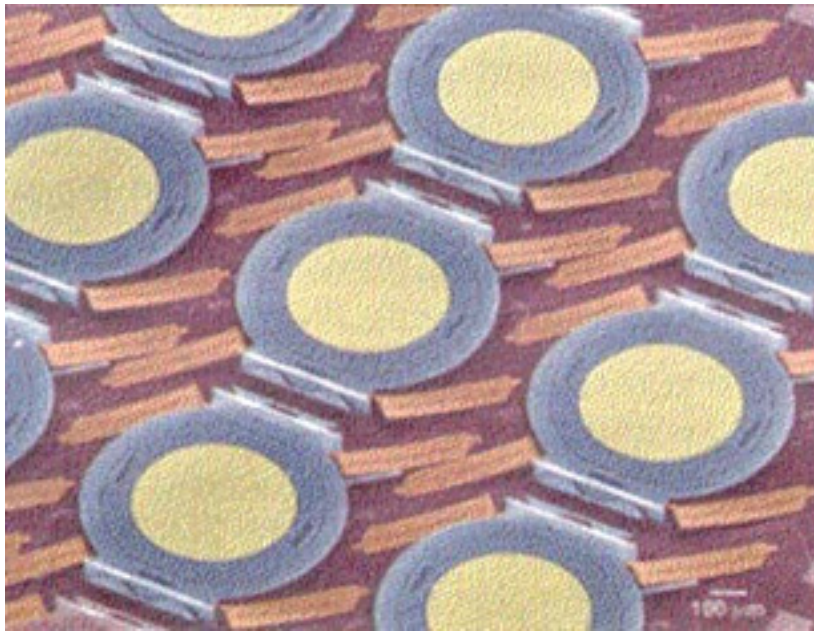
Specifications

Mirror size:	520 μm across
Reflective area:	510 μm across
Shape:	Octagonal
Mirror thickness:	13 μm
Surface roughness:	< 8 \AA rms
Surface reflectivity:	> 95% at 630 nm (gold)
Bias voltage:	35 to 55 Volts
Drive voltage:	0 to 110 Volts (0 to 2X Bias)
Resonant rotation frequency:	outer axis 1.3 kHz, inner axis 1.8 kHz
Operating Temperature:	0 to 50 $^{\circ}\text{C}$
Radius of Curvature:	> 0.4 meters within operating temperature
Product number:	029157

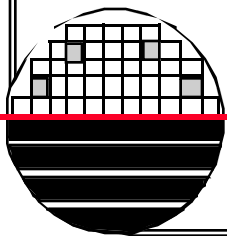
www.memsoptical.com

MIRRORS

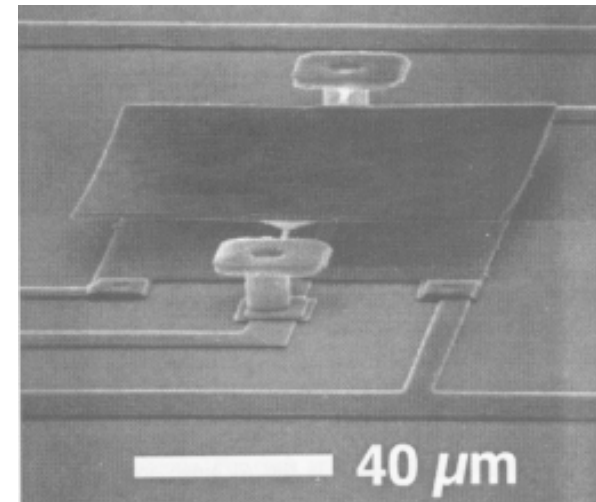
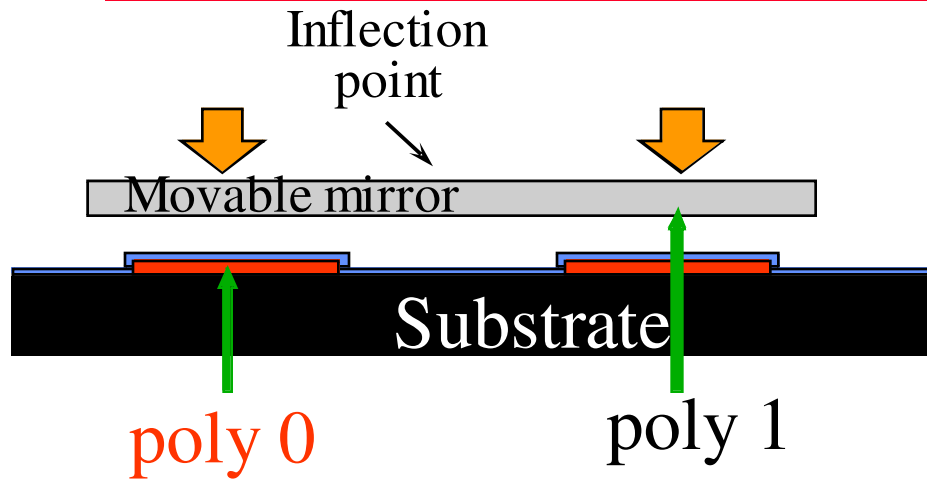
MOEMs - Micro Optical Electro Mechanical Systems



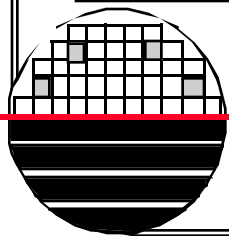
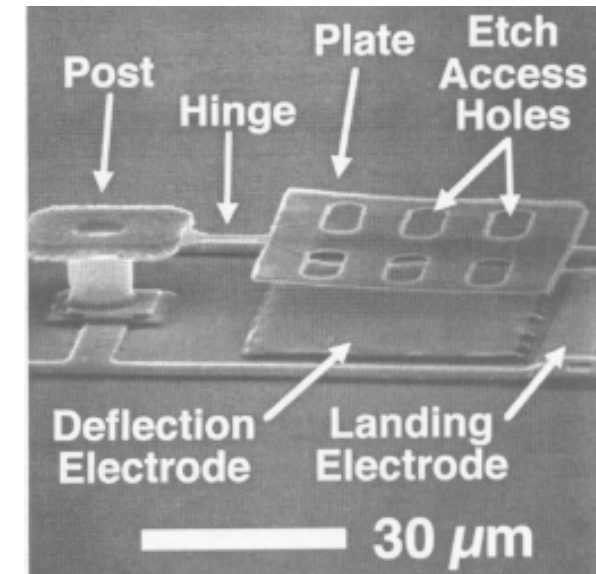
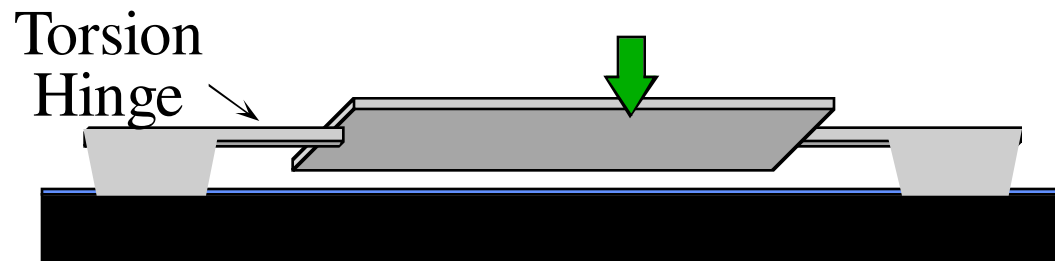
Lucent Technologies –
Lambda router, 256 mirror fiber optic multiplexer



TORSION - MIRROR

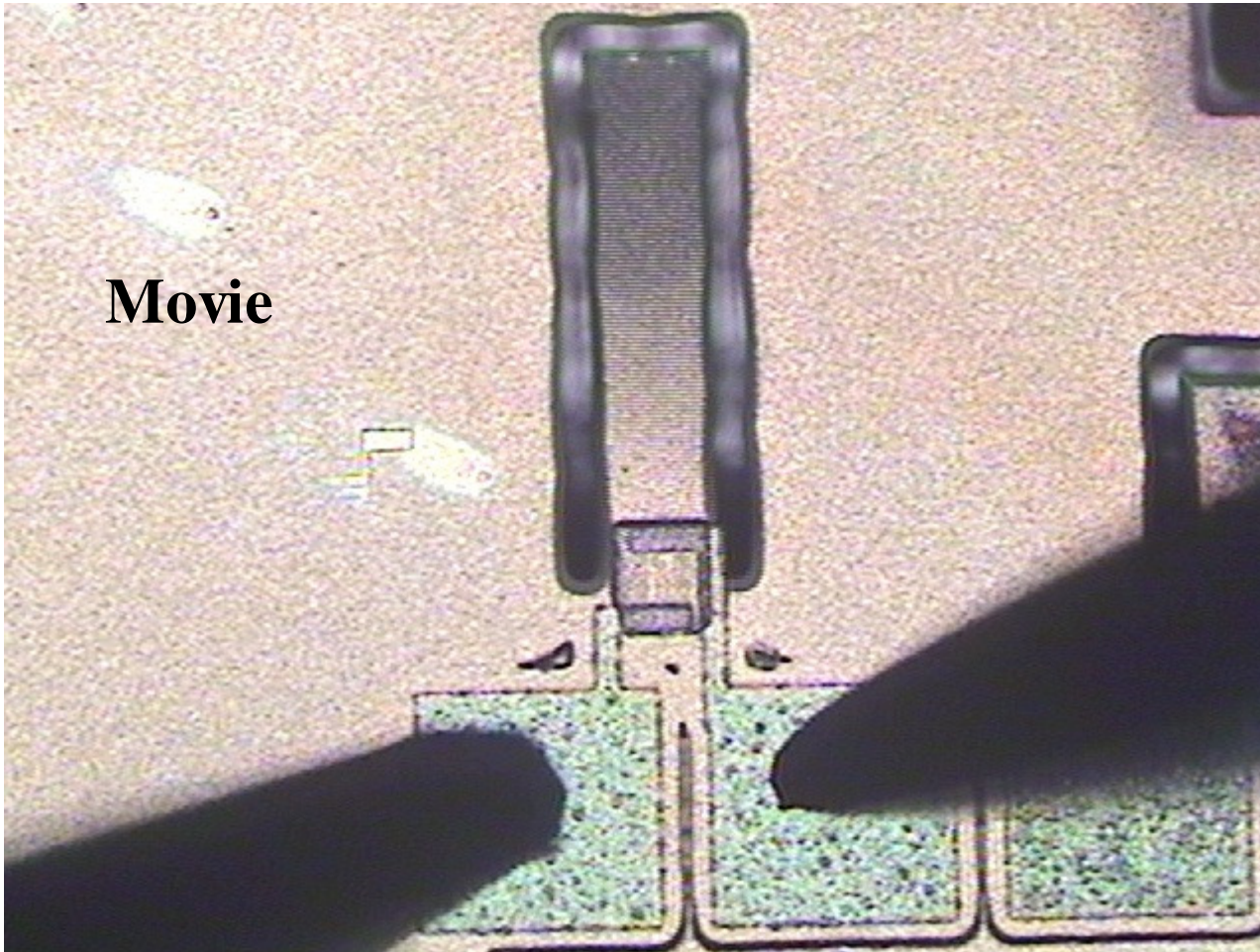


Micro-mirror Perspective View



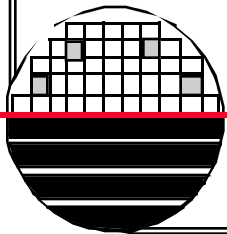
POLYIMIDE ON HEATER

Movie



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Jeremiah Hebding

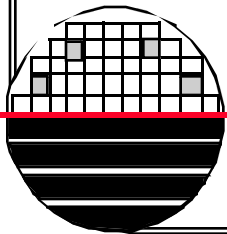


THERMALLY ACTUATED MEMS MICRO MIRROR

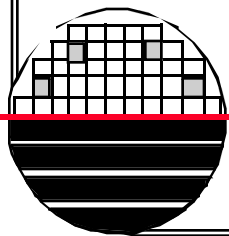
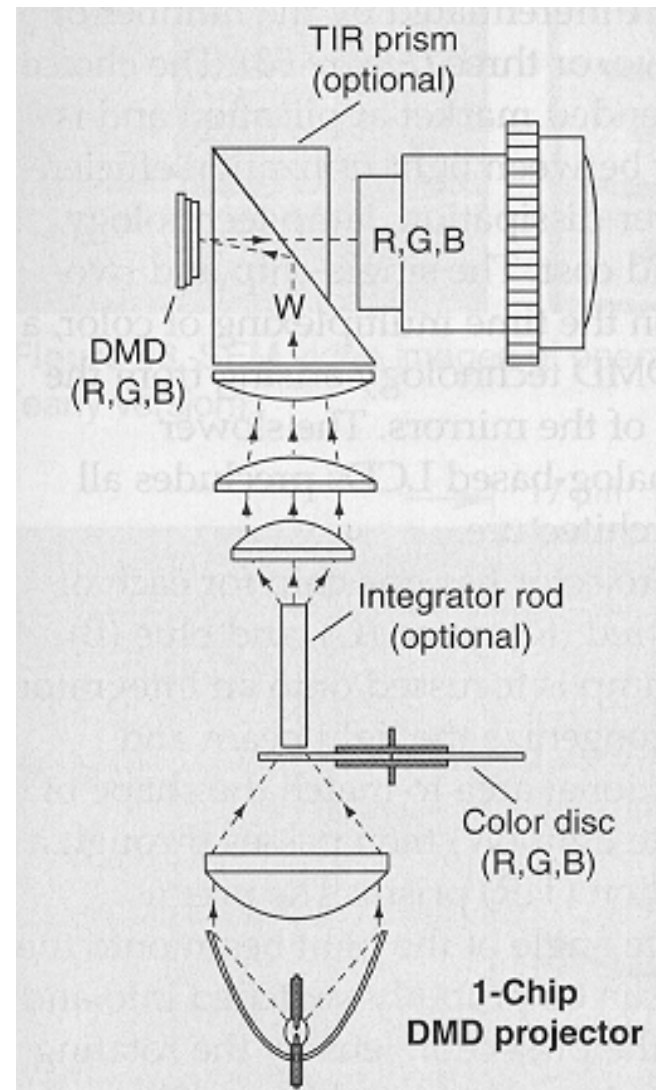


**Thermal Mirror
Microactuator**

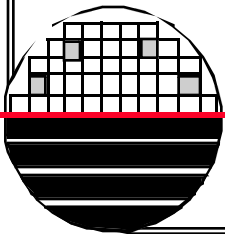
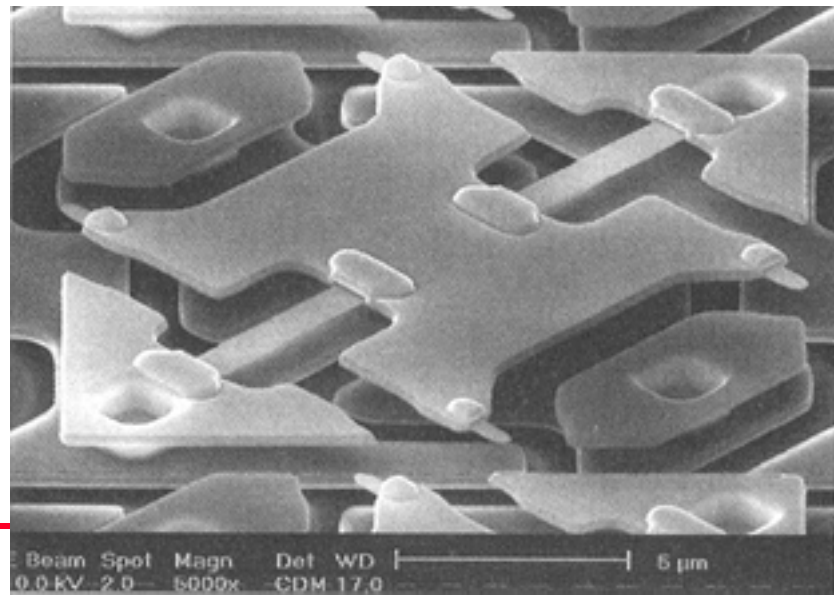
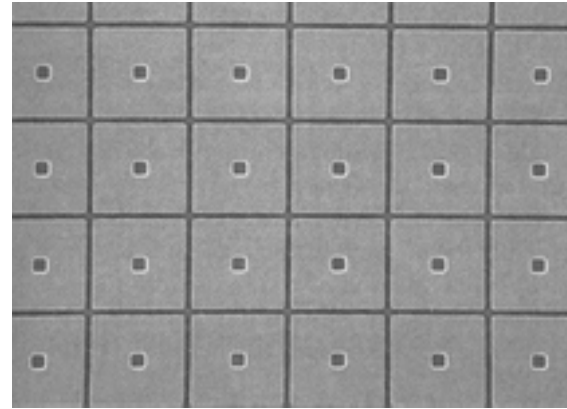
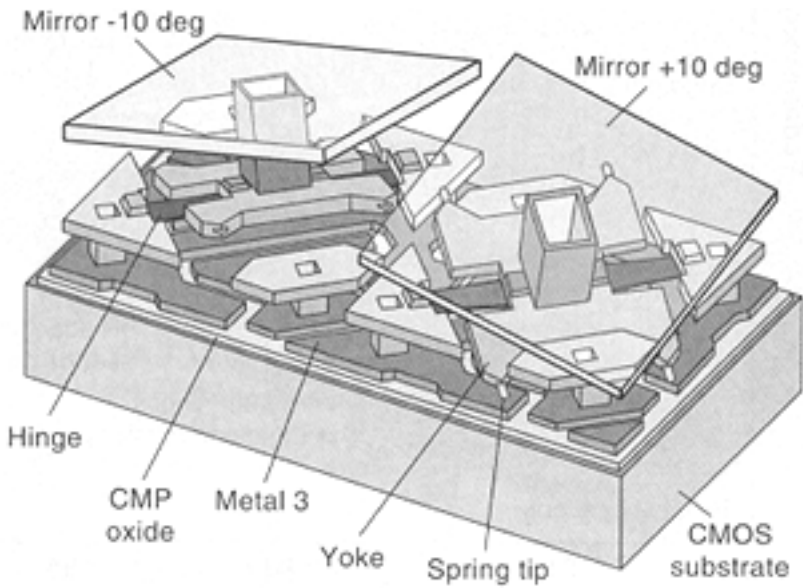
**Dr. Lynn Fuller
Rakesh Dhull**



DIGITAL MIRROR LIGHT PROJECTION SYSTEM



TORSIONAL MIRRORS

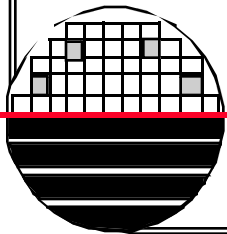


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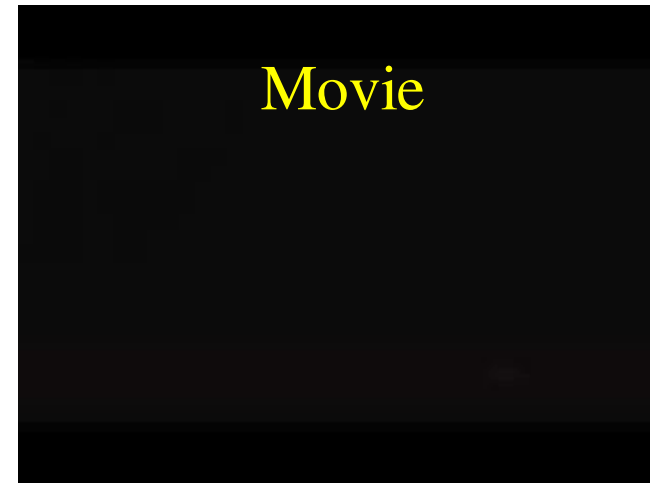
TI MICROMIRROR PROJECTOR



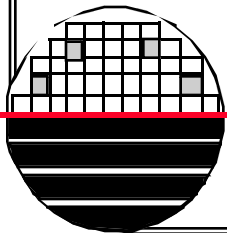
Microelectronic Engineering



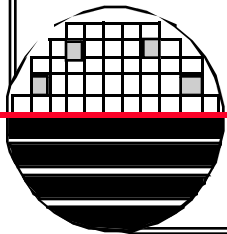
TEXAS INSTRUMENTS DIGITAL PROJECTION PRODUCTS



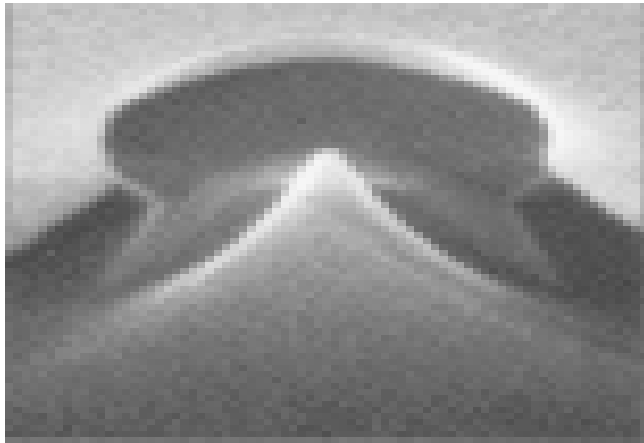
www.TI.com



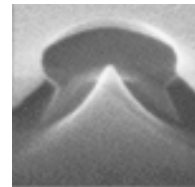
DXtreme PRO1



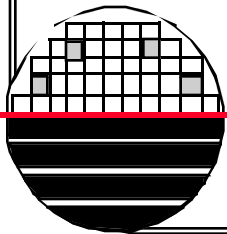
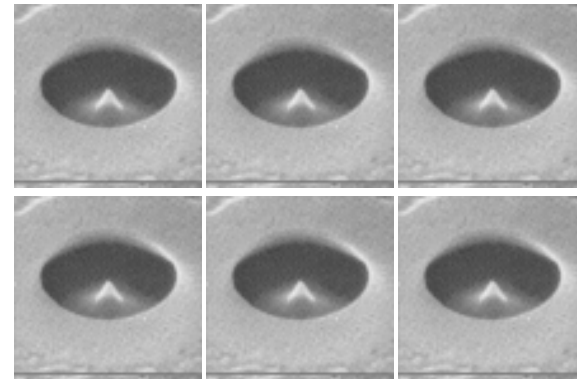
**FIELD EMISSION TIPS FOR
FLAT PANNEL DISPLAYS**



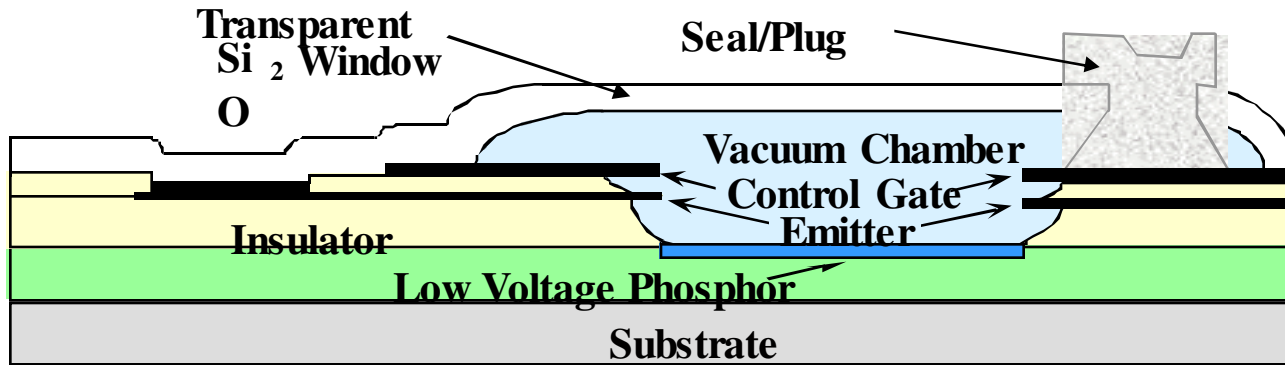
1 μ m
→ ←



**Alex Raub, 1995, now at
National Semiconductor
Santa Clara, CA**

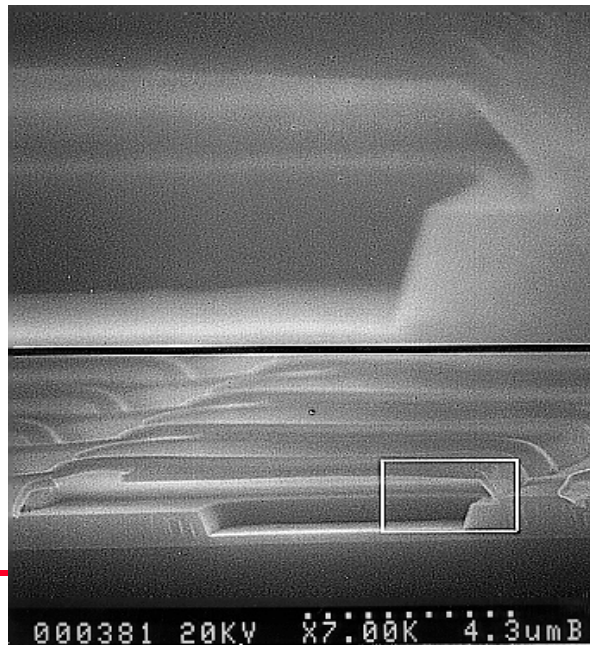


FIELD EMISSION FLAT PANNEL DISPLAYS

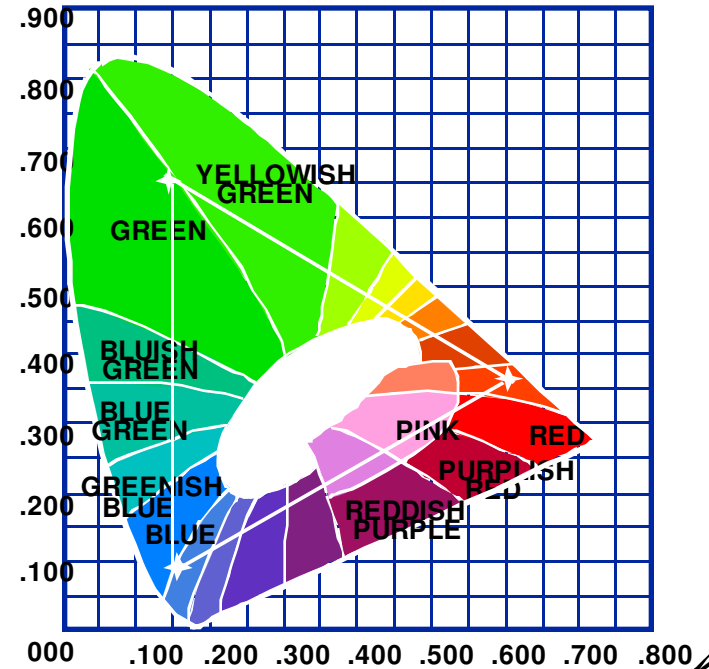


Integrated Phosphor Field Emission Device

Micro-encapsulated Chamber



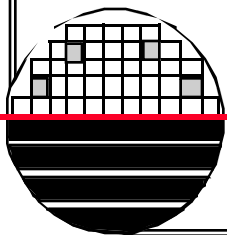
Color Chart of AVT Phosphors



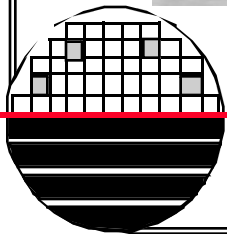
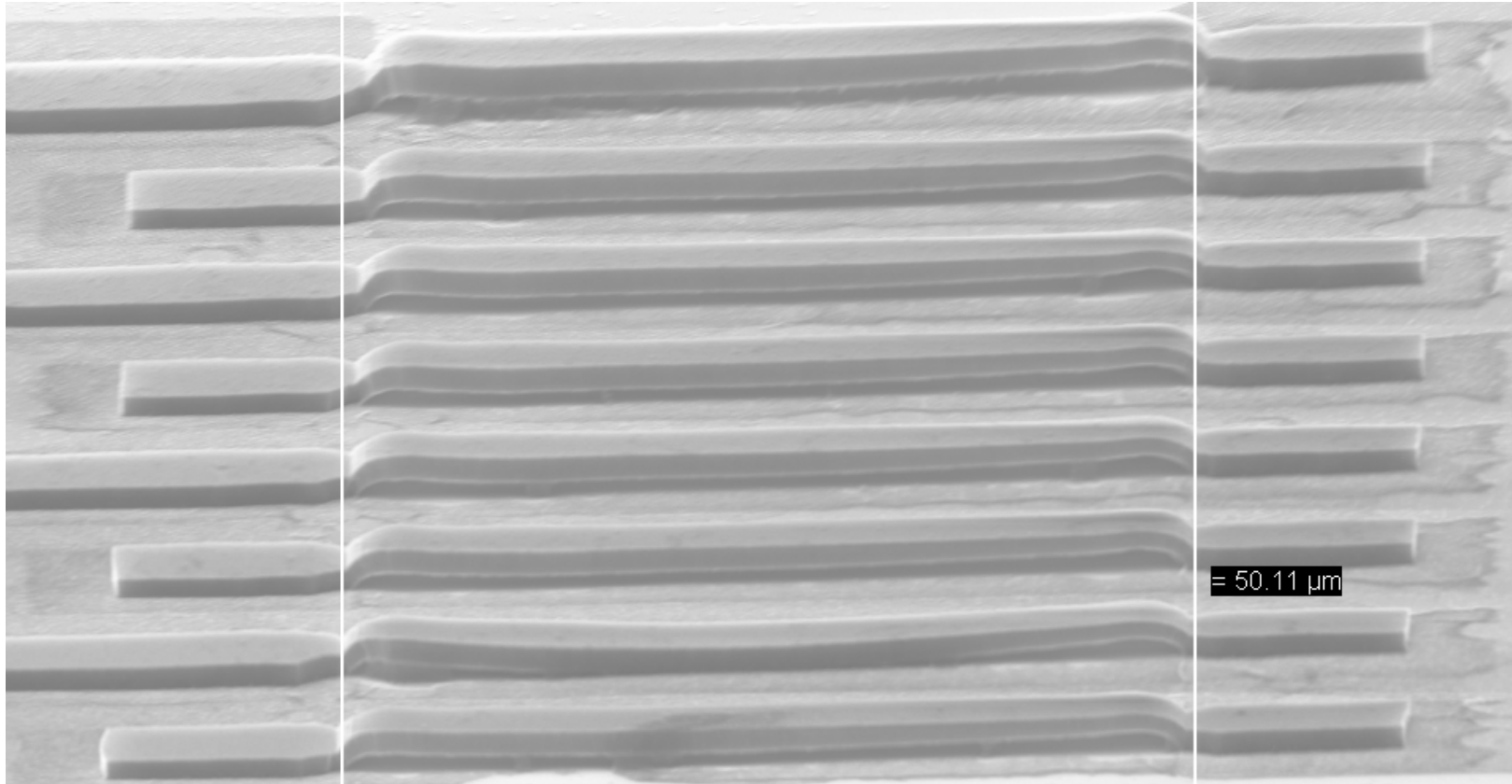
REFLECTIVE MECHANICAL LIGHT MODULATOR

Modulator Type	Motion	Side and Top Views
Cantilever Beam	Bending	
Torsional Plate	Rotation about Torsion Axis	
Membrane	Drumhead	
Suspended Plate	Vertical	

Rochester Microelect Table comparing four basic surface micromachined reflective mechanical light modulator designs. Each design has different sensitivities to geometries, thin-film properties, squeeze-film damping, etc.



RIT LIGHT MODULATOR - SENIOR PROJECT

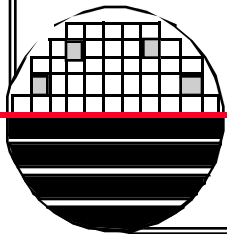


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Sushil Shakya

REFERENCES

1. Micro Spectro Photometer by Marion Jess, Carl Duisberg Gesellschaft e.V., Fachhochschule Koln, Germany , August 1996.
2. Fundamentals of Microfabrication, Marc Madou, CRC Press, LLC, 1997.
3. Scientific Measurement Systems, Inc., 2527 Foresight Circle, Grand Junction, CO 81505-1007.
4. Micromachined Transducers, Gregory T. A. Kovacs, McGraw-Hill, 1998
5. Solar Cells, Martin A. Green, Prentice-Hall



HOMEWORK – OPTICAL BASICS FOR MEMS

1. If the human body is thought of as a black body light source. What types of optical detector will be able to sense a human by sensing its IR emission? Explain.
2. Look up the Texas Instruments Digital Light Projector products. What is the cost of a developer kit for some of their projection products.
3. Visit the following web sites and discuss one product of interest for each.
www.silicon-sensor.com
www.heimannsensor.com
www.oceanoptics.com
www.memsoptical.com

